



US009219196B2

(12) **United States Patent**  
**Seo et al.**

(10) **Patent No.:** **US 9,219,196 B2**  
(45) **Date of Patent:** **Dec. 22, 2015**

(54) **WAFER-LEVEL LIGHT EMITTING DIODE PACKAGE AND METHOD OF FABRICATING THE SAME**

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(\*) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 0 days.

(21) Appl. No.: **14/708,029**

(22) Filed: **May 8, 2015**

(65) **Prior Publication Data**

US 2015/0243844 A1 Aug. 27, 2015

**Related U.S. Application Data**

(63) Continuation of application No. 13/194,317, filed on Jul. 29, 2011, now Pat. No. 9,070,851.

(30) **Foreign Application Priority Data**

Sep. 24, 2010 (KR) ..... 10-2010-0092807  
Sep. 24, 2010 (KR) ..... 10-2010-0092808

(51) **Int. Cl.**

**H01L 33/00** (2010.01)  
**H01L 33/24** (2010.01)

(Continued)

(52) **U.S. Cl.**

CPC ..... **H01L 33/24** (2013.01); **H01L 33/38** (2013.01); **H01L 33/486** (2013.01);  
(Continued)

(58) **Field of Classification Search**

CPC . H01L 33/0079; H01L 33/005; H01L 33/385;  
H01L 33/87  
USPC ..... 438/24–27, 105–118  
See application file for complete search history.

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*Primary Examiner* — Cuong Q Nguyen

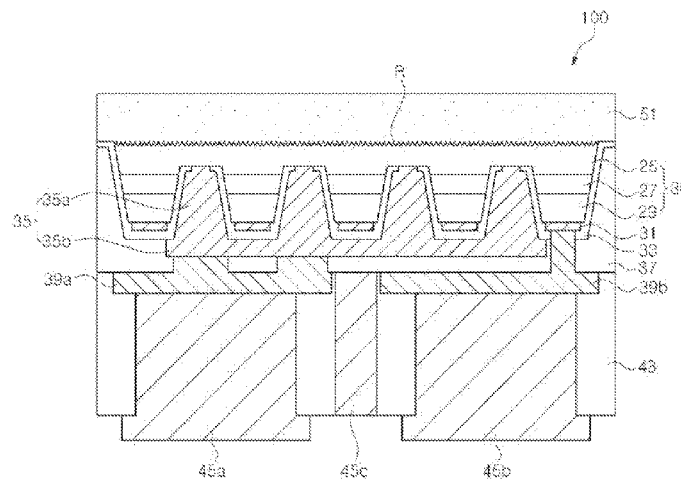
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(57)

**ABSTRACT**

Exemplary embodiments of the present invention provide a wafer-level light emitting diode (LED) package and a method of fabricating the same. The LED package includes a semiconductor stack including a first conductive type semiconductor layer, an active layer, and a second conductive type semiconductor layer; a plurality of contact holes arranged in the second conductive type semiconductor layer and the active layer, the contact holes exposing the first conductive type semiconductor layer; a first bump arranged on a first side of the semiconductor stack, the first bump being electrically connected to the first conductive type semiconductor layer via the plurality of contact holes; a second bump arranged on the first side of the semiconductor stack, the second bump being electrically connected to the second conductive type semiconductor layer; and a protective insulation layer covering a sidewall of the semiconductor stack.

**22 Claims, 19 Drawing Sheets**



(51) **Int. Cl.***H01L 33/50* (2010.01)*H01L 33/64* (2010.01)*H01L 33/38* (2010.01)*H01L 33/48* (2010.01)(52) **U.S. Cl.**

CPC ..... *H01L 33/507* (2013.01); *H01L 33/642*  
 (2013.01); *H01L 2933/0016* (2013.01); *H01L*  
*2933/0025* (2013.01); *H01L 2933/0033*  
 (2013.01); *H01L 2933/0041* (2013.01); *H01L*  
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Figure 1

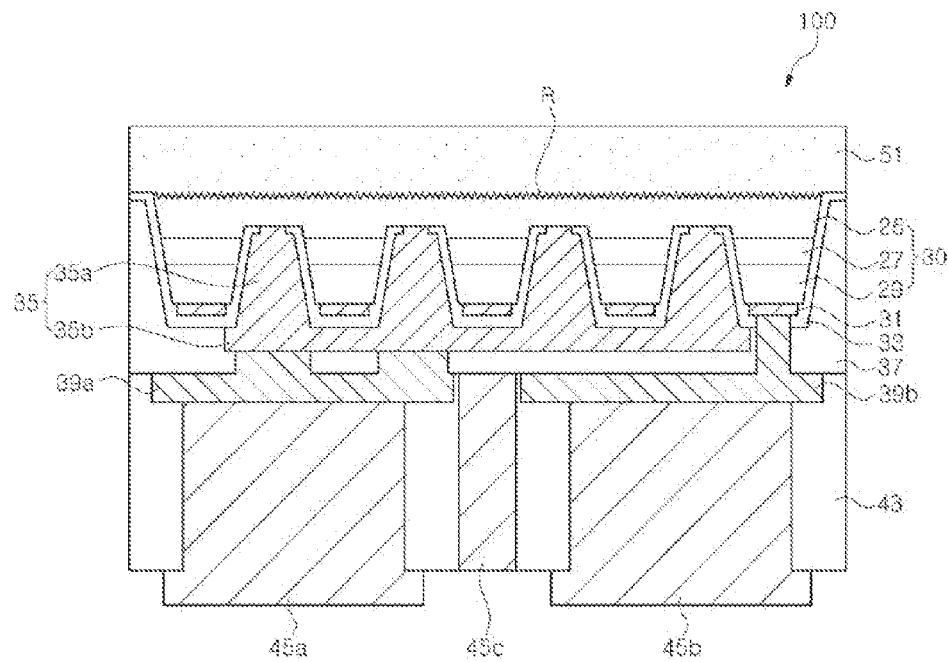


Figure 2

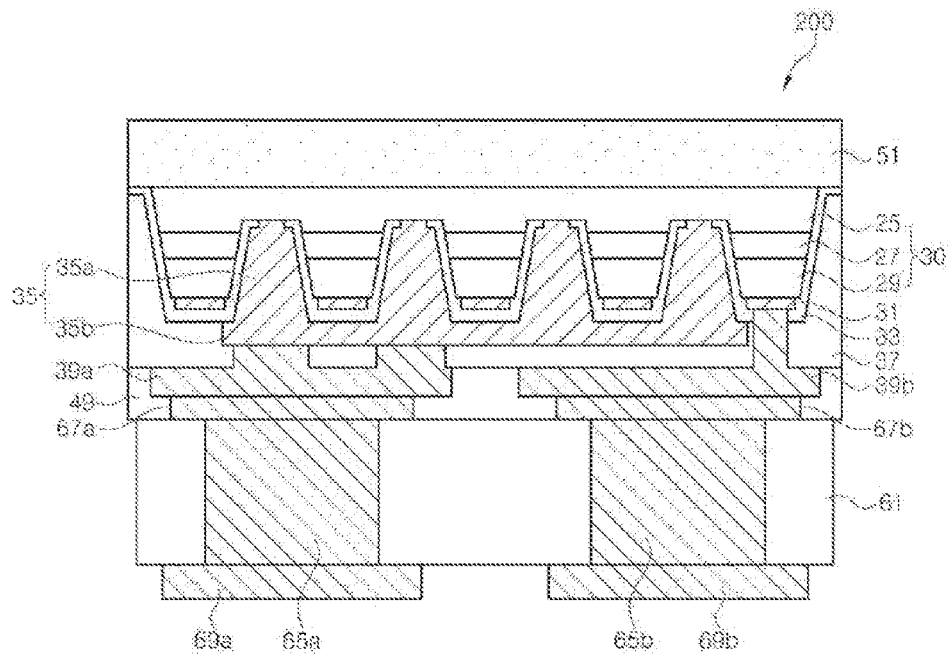


Figure 3

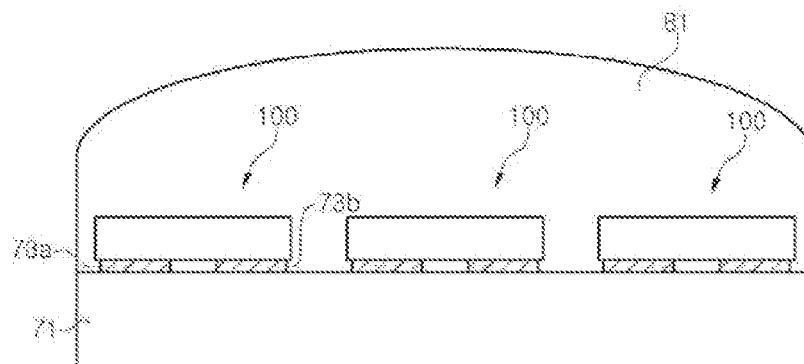


Figure 4

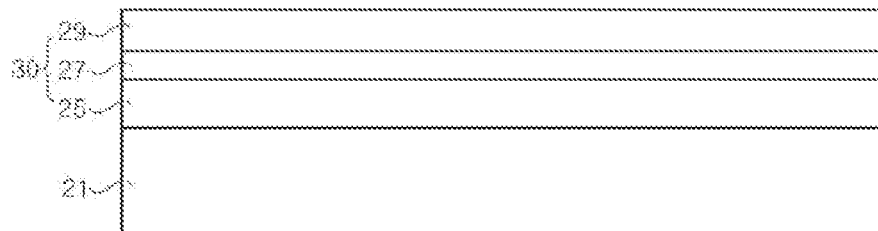


Figure 5

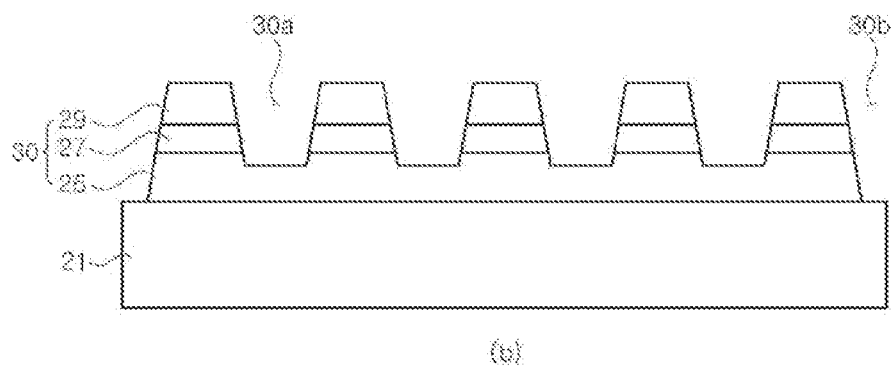
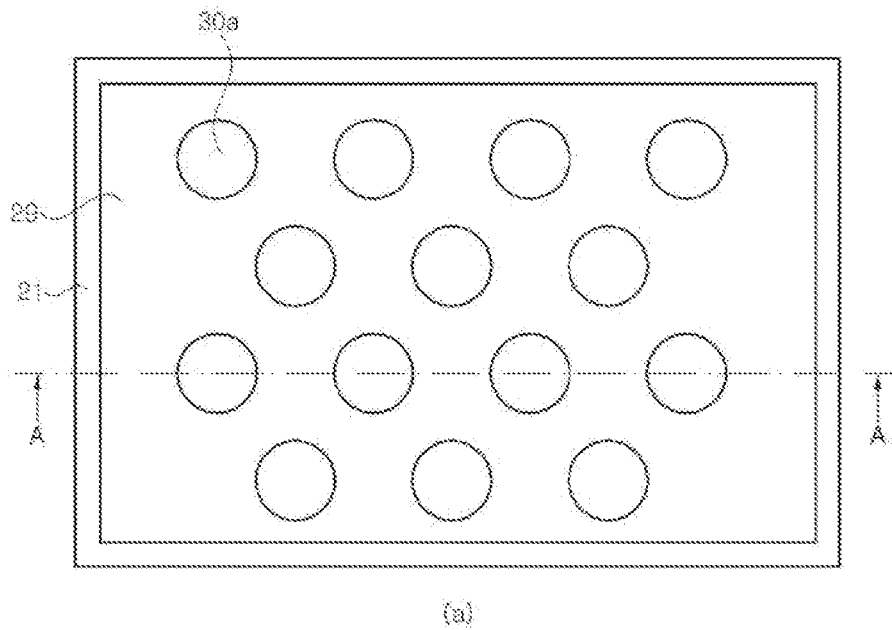


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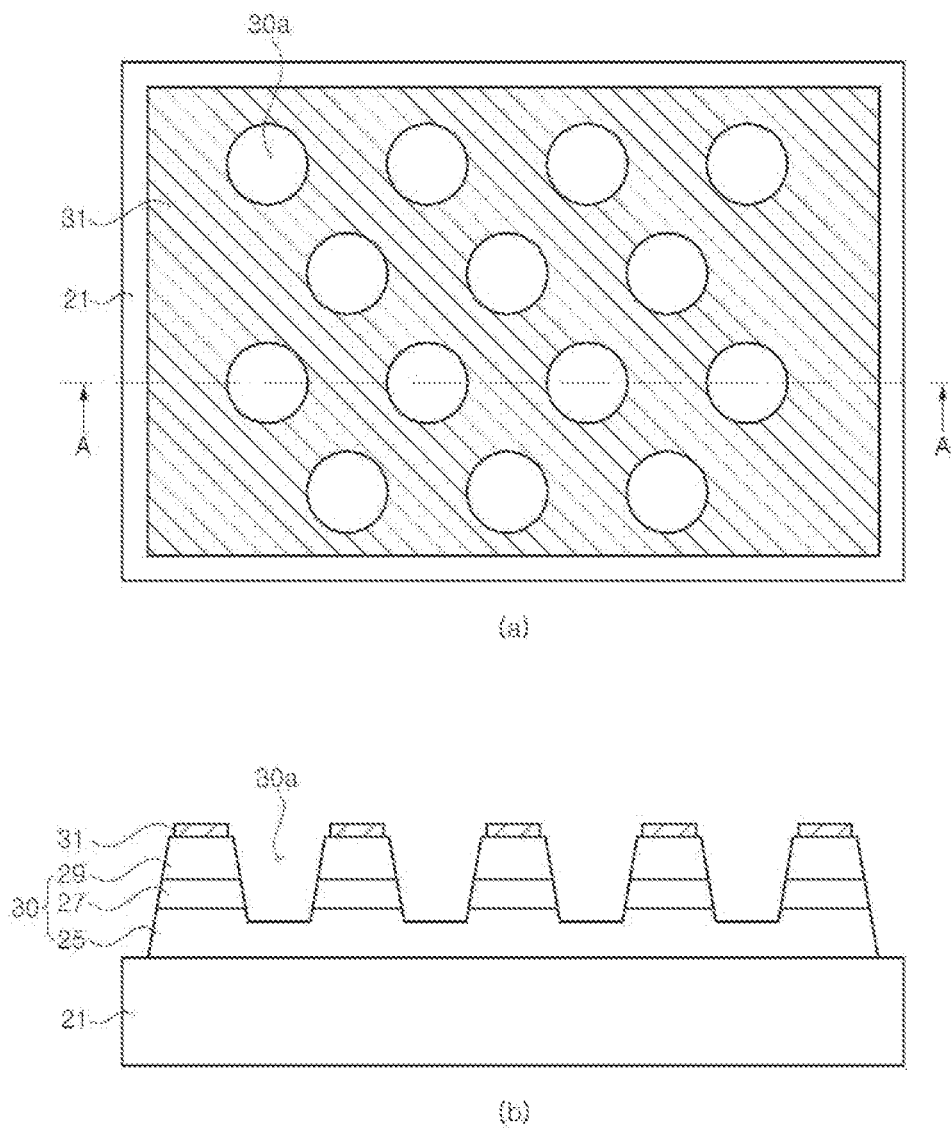


Figure 7

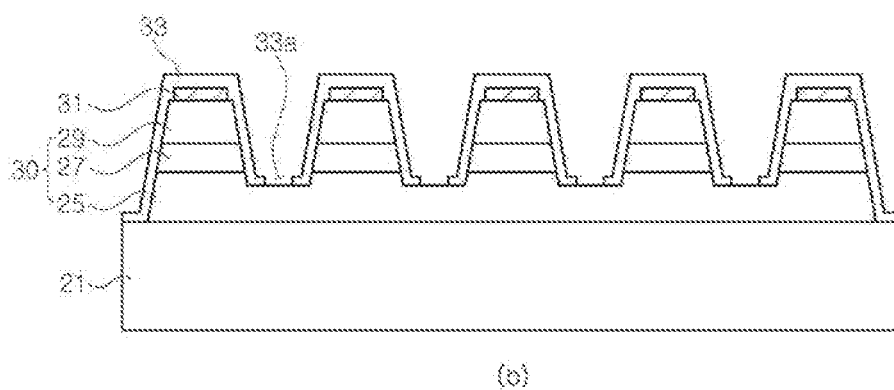
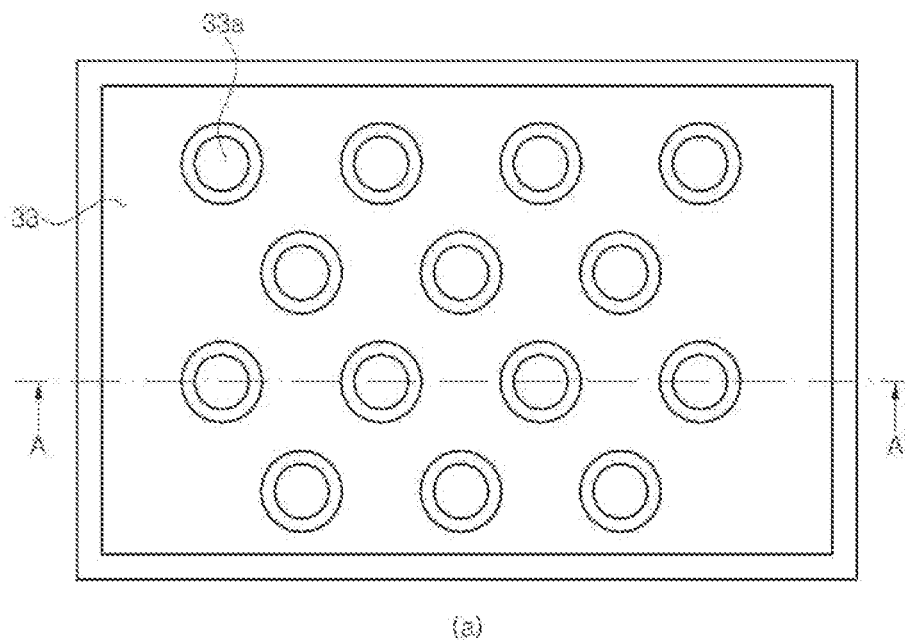
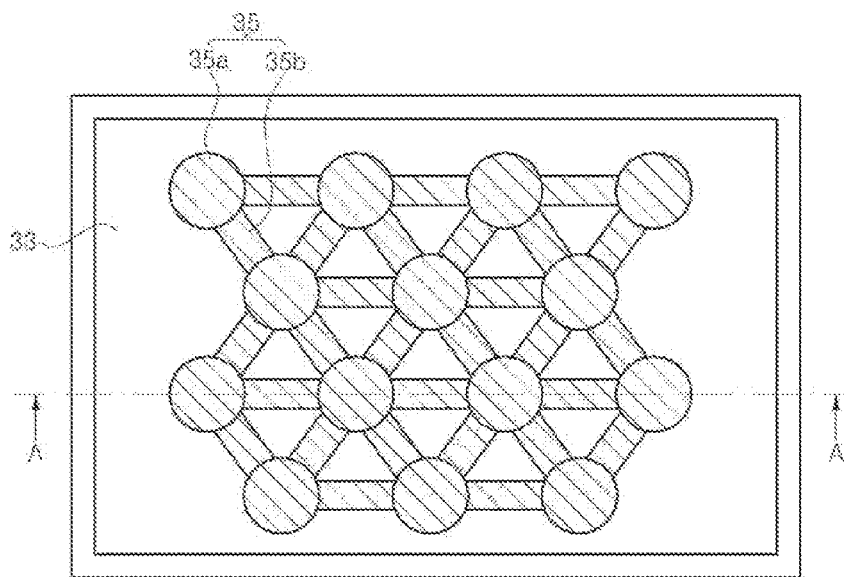
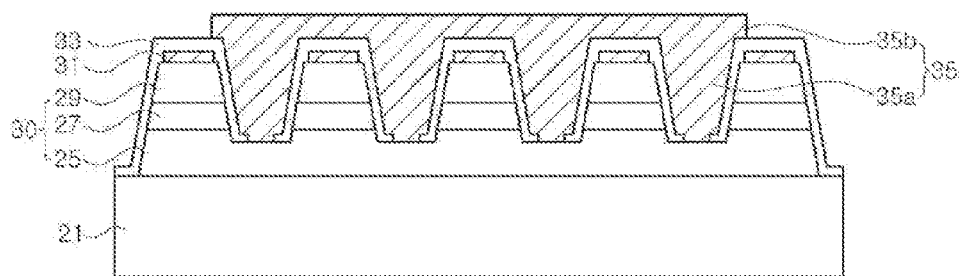


Figure 8



(a)



(b)



Figure 9

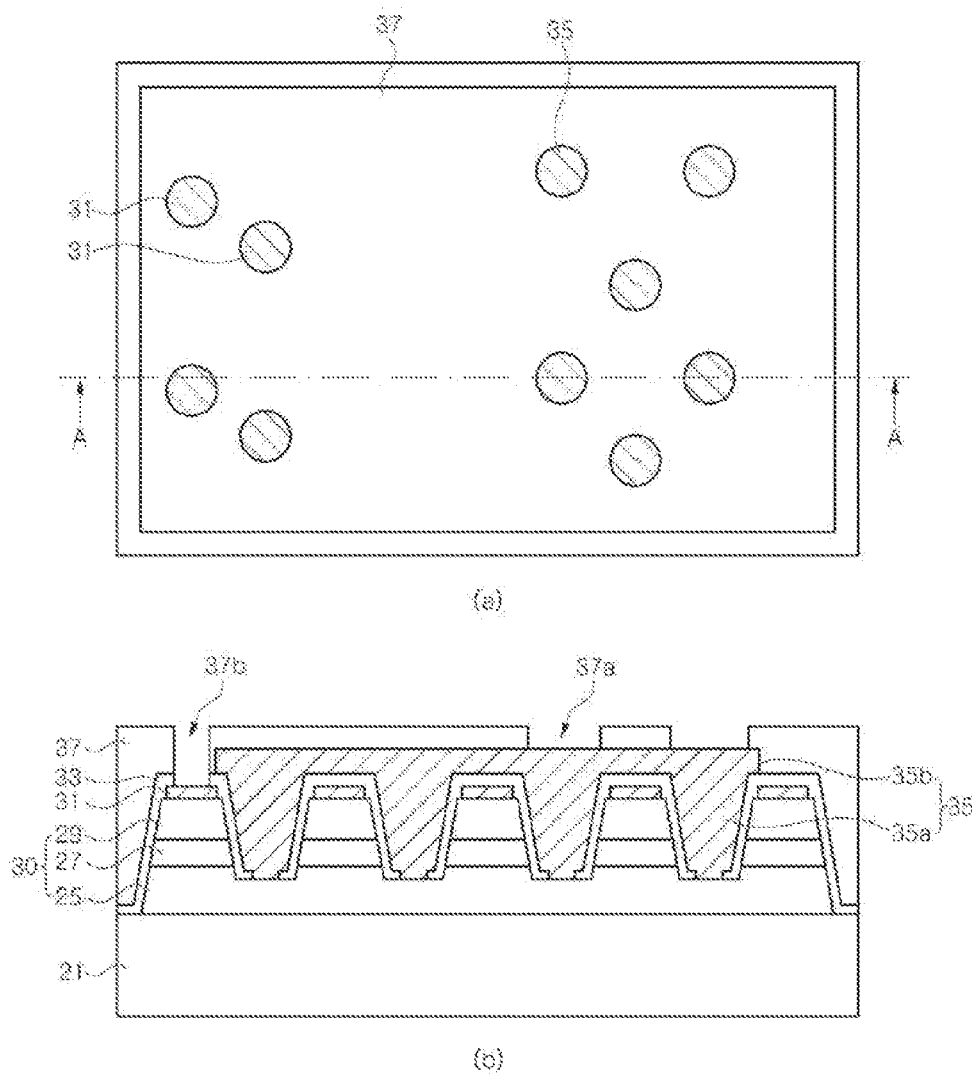


Figure 10

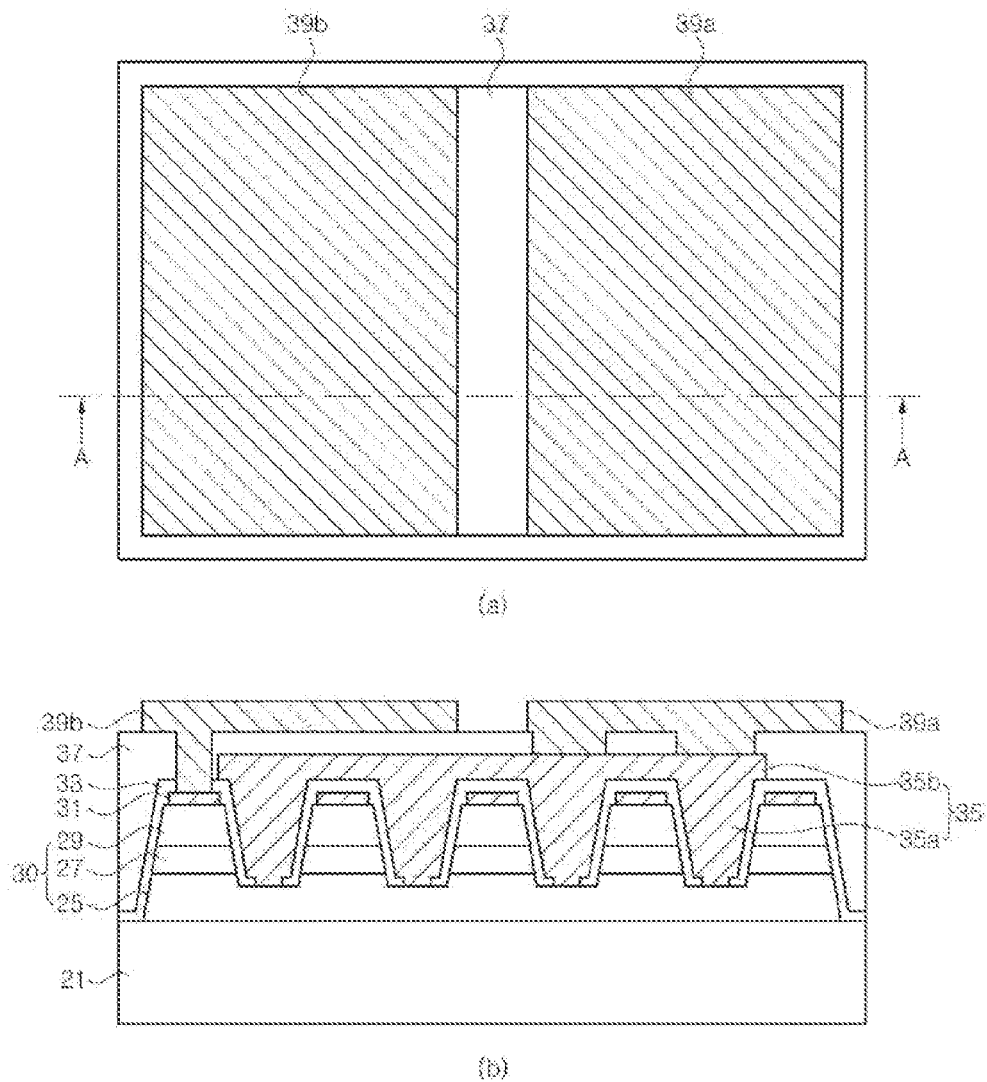


Figure 11

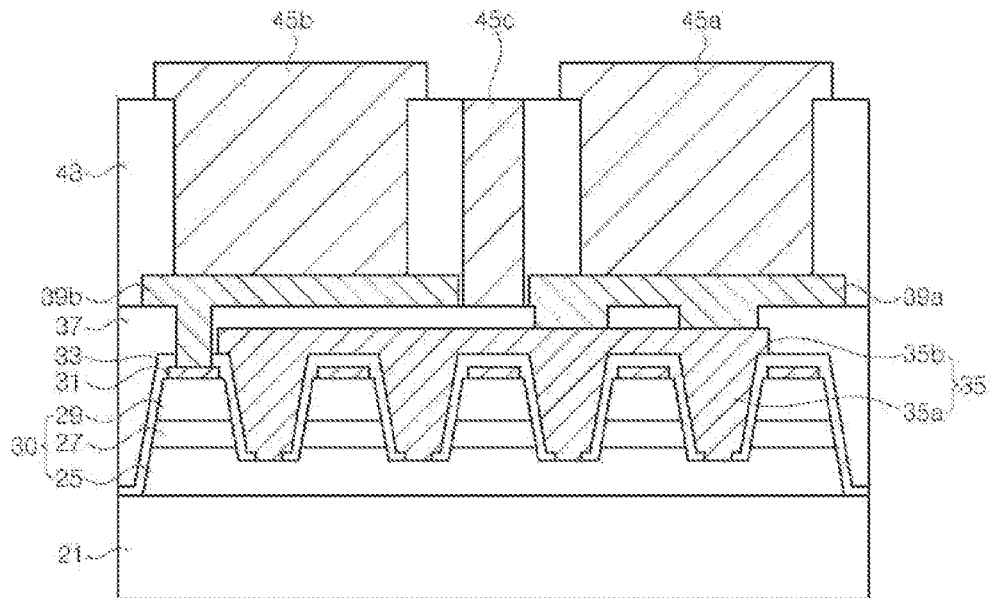
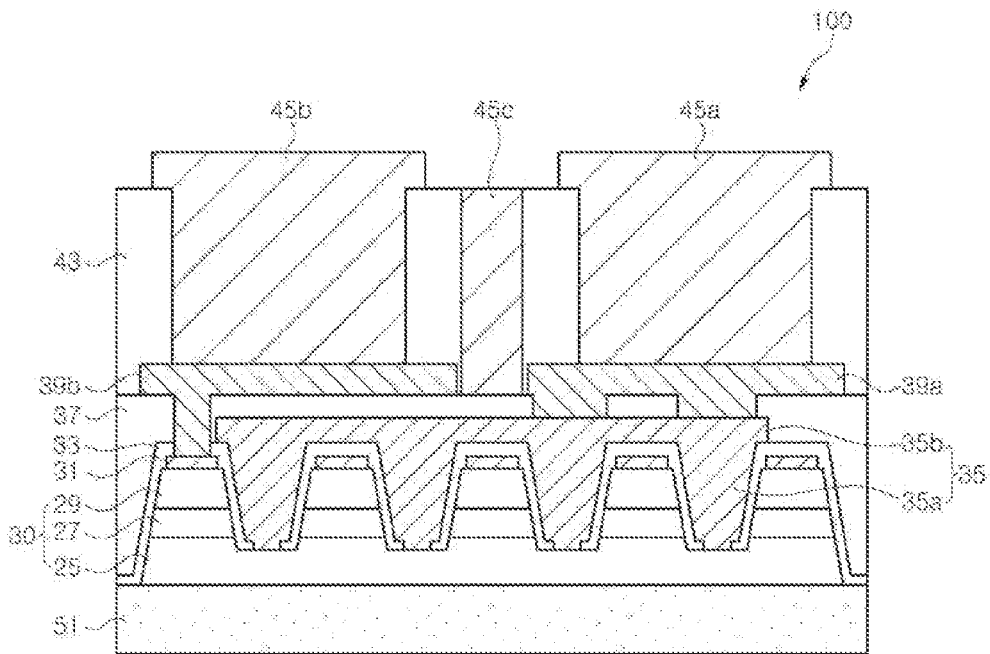


Figure 12



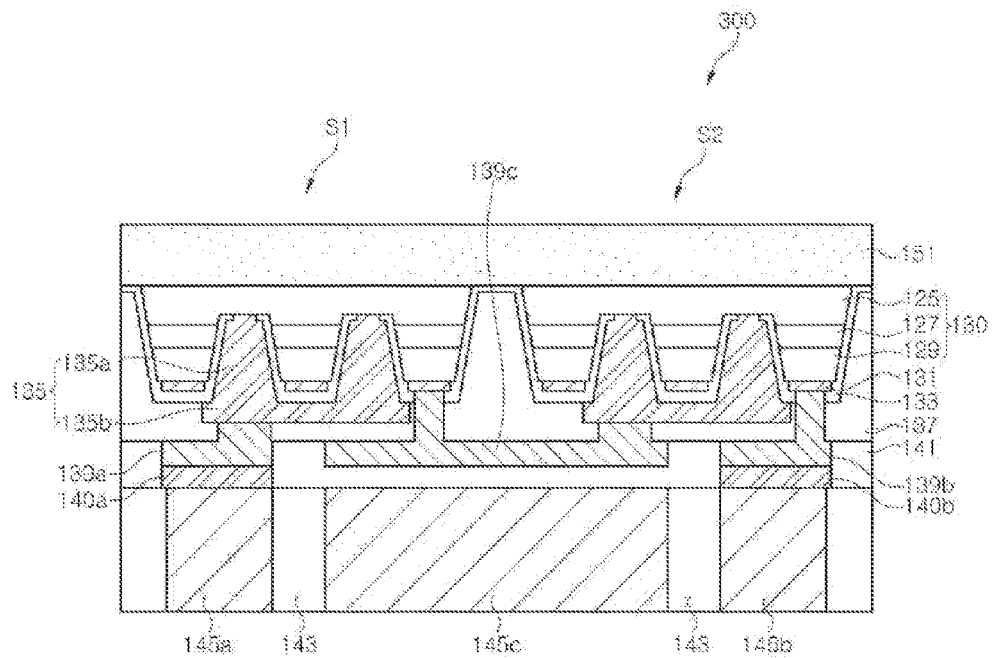


Figure 15

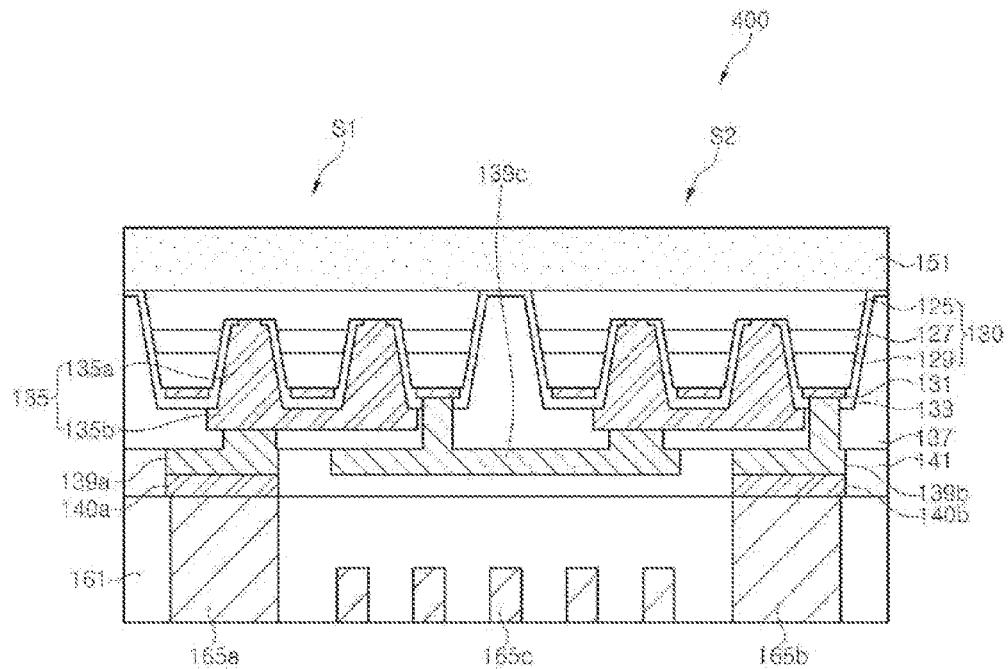


Figure 16

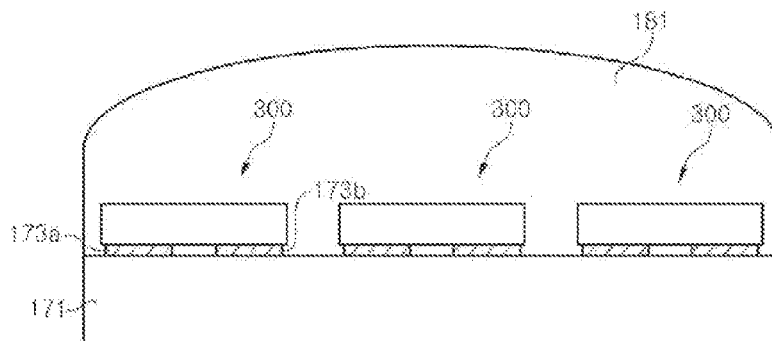


Figure 17

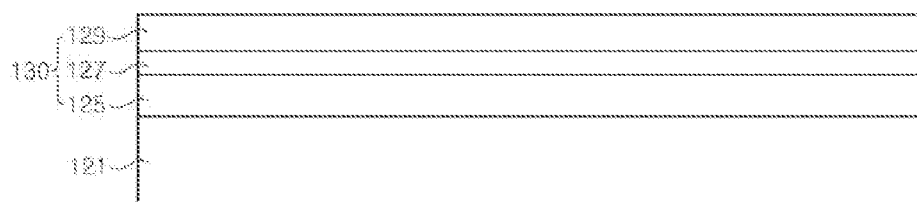


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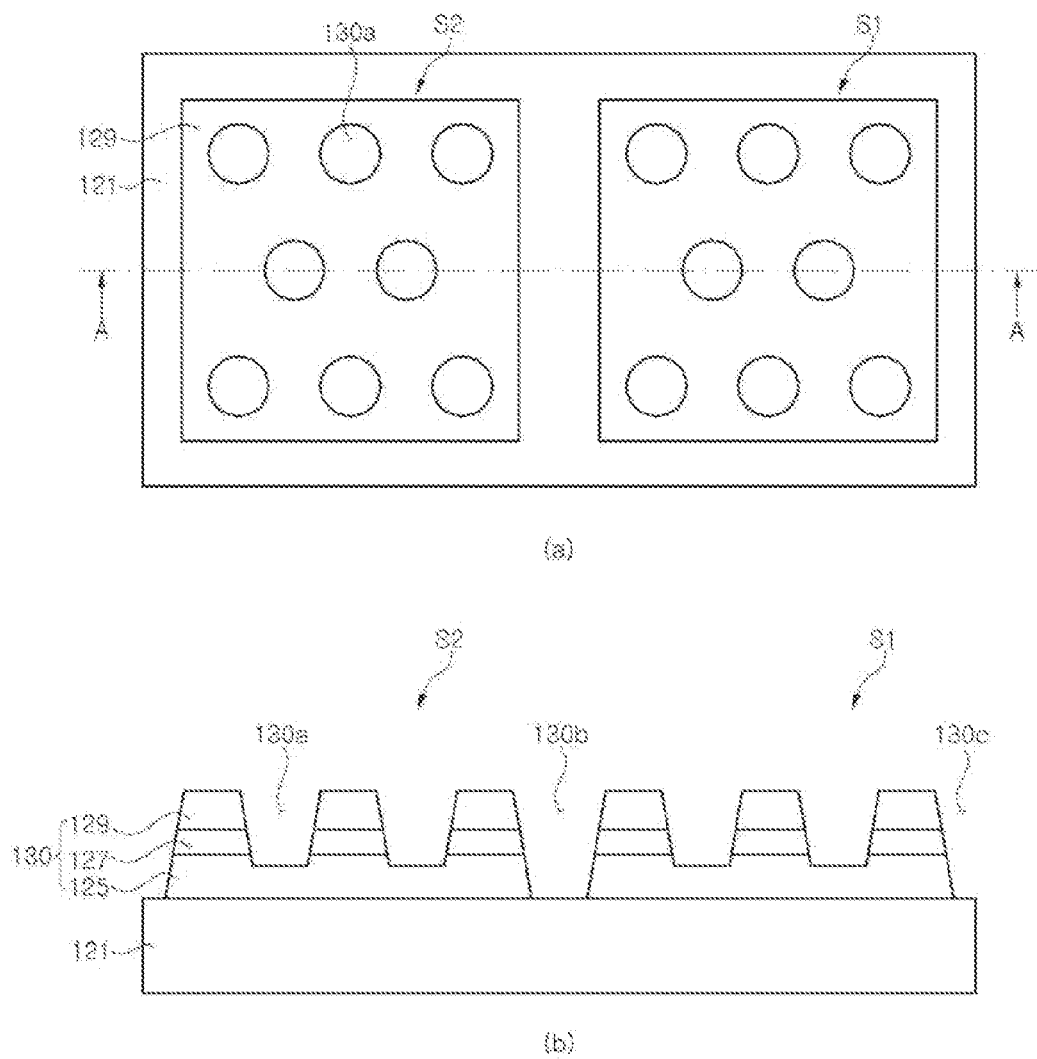


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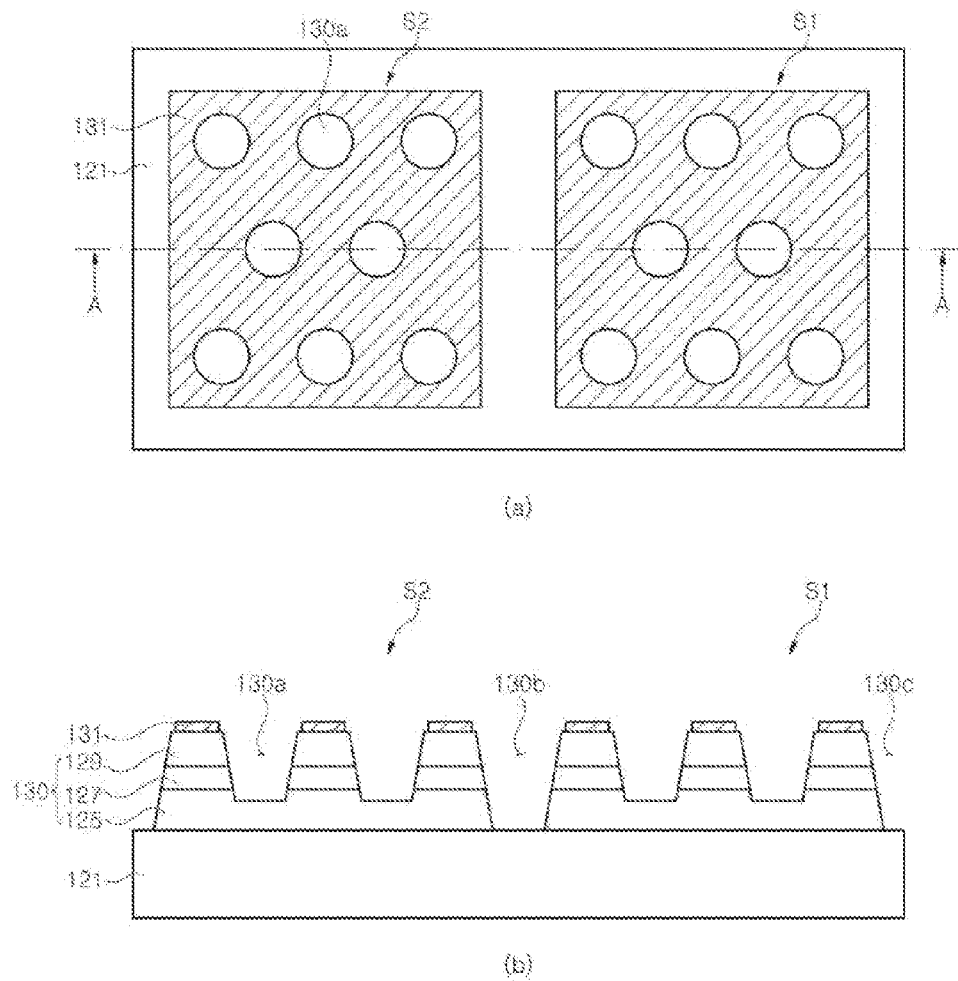


Figure 20

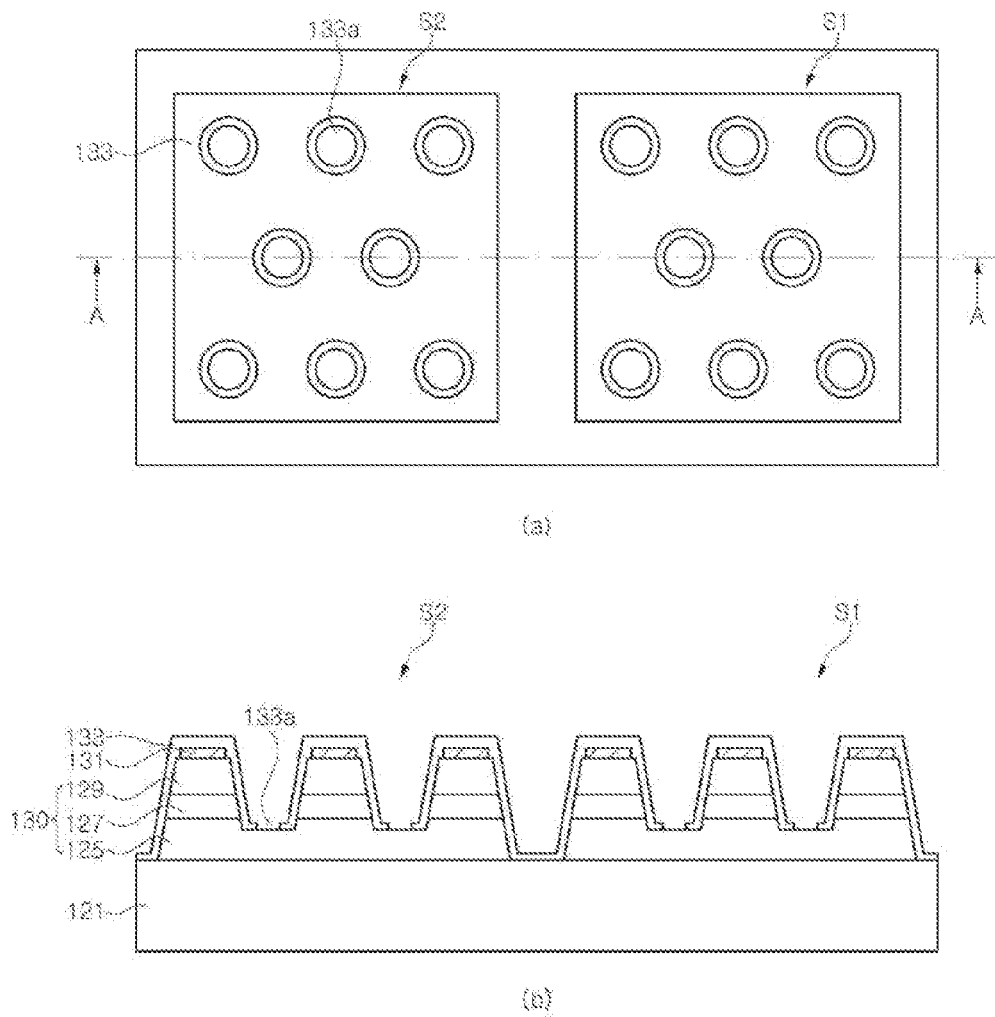




Figure 21

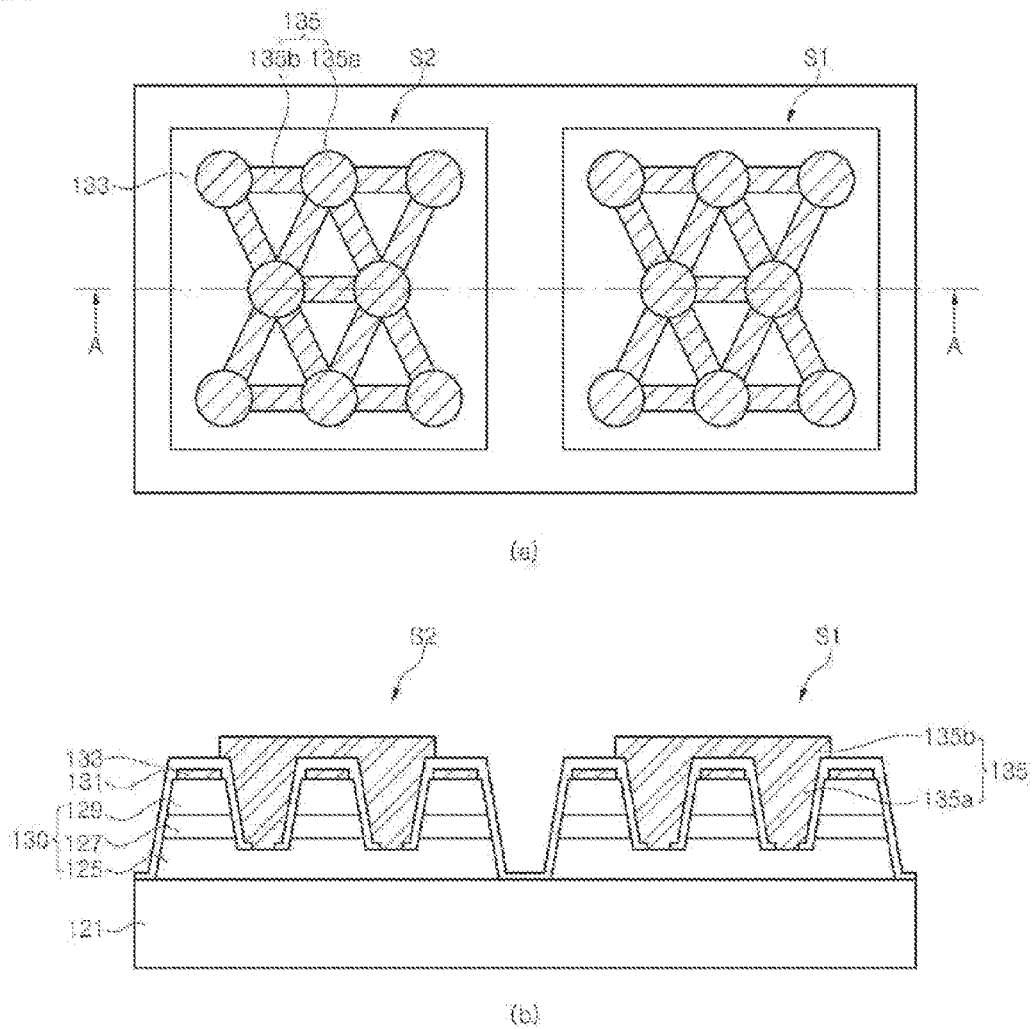


Figure 22

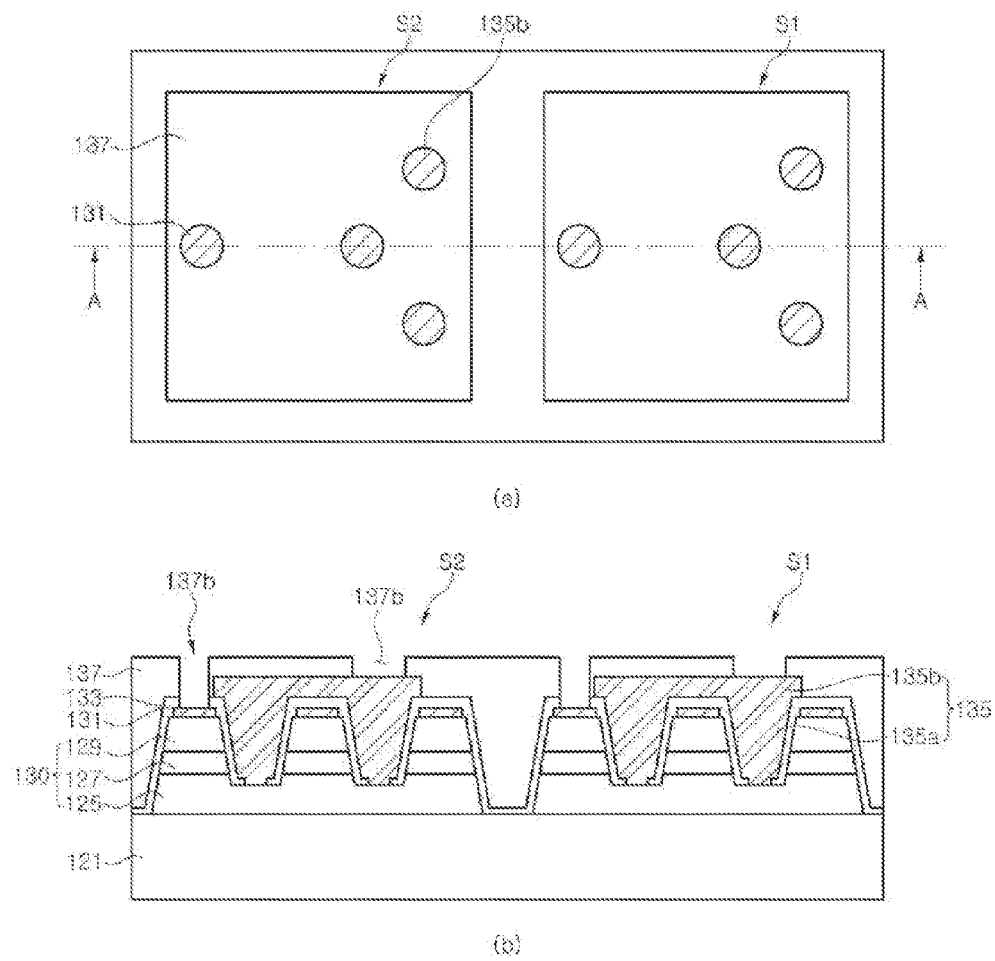


Figure 23

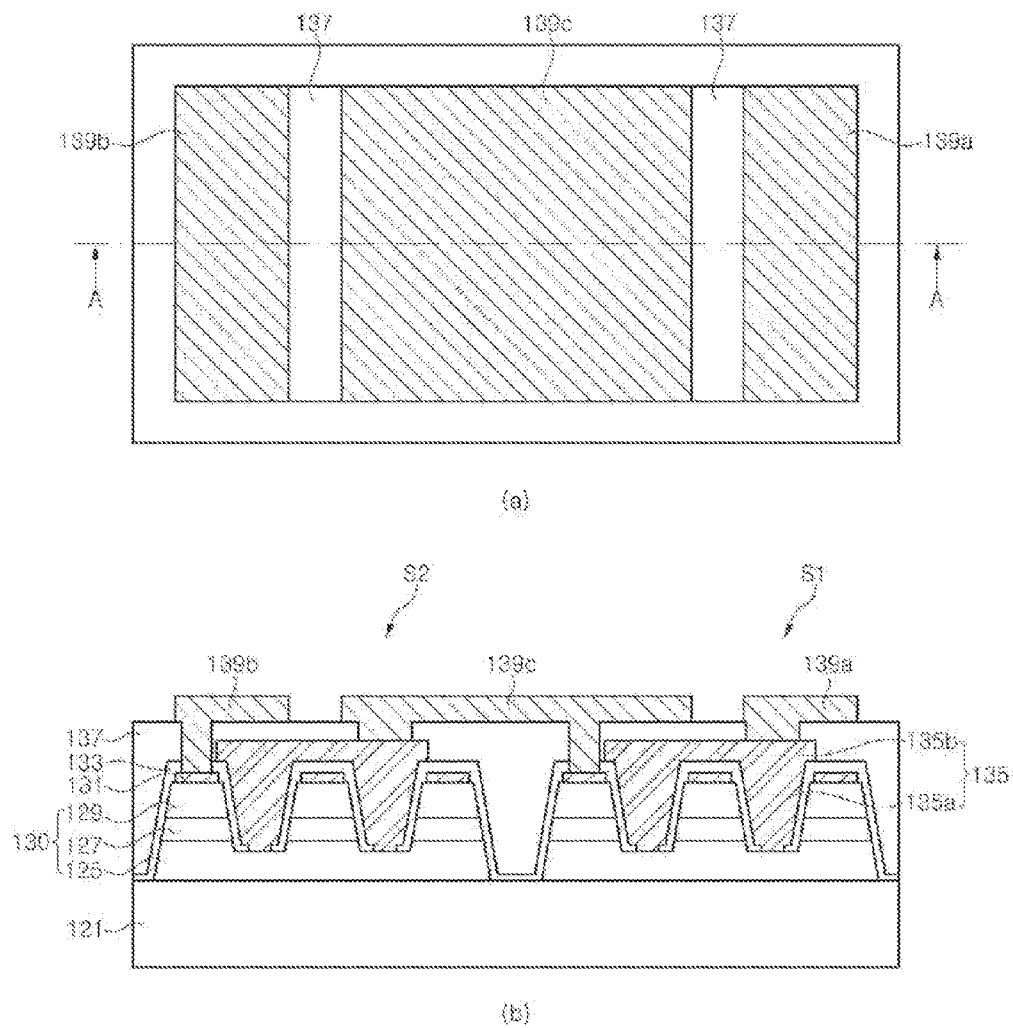


Figure 24

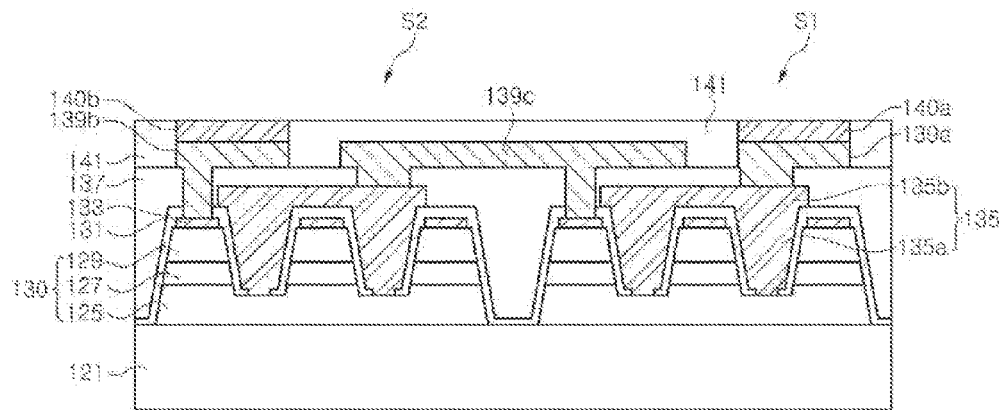


Figure 25

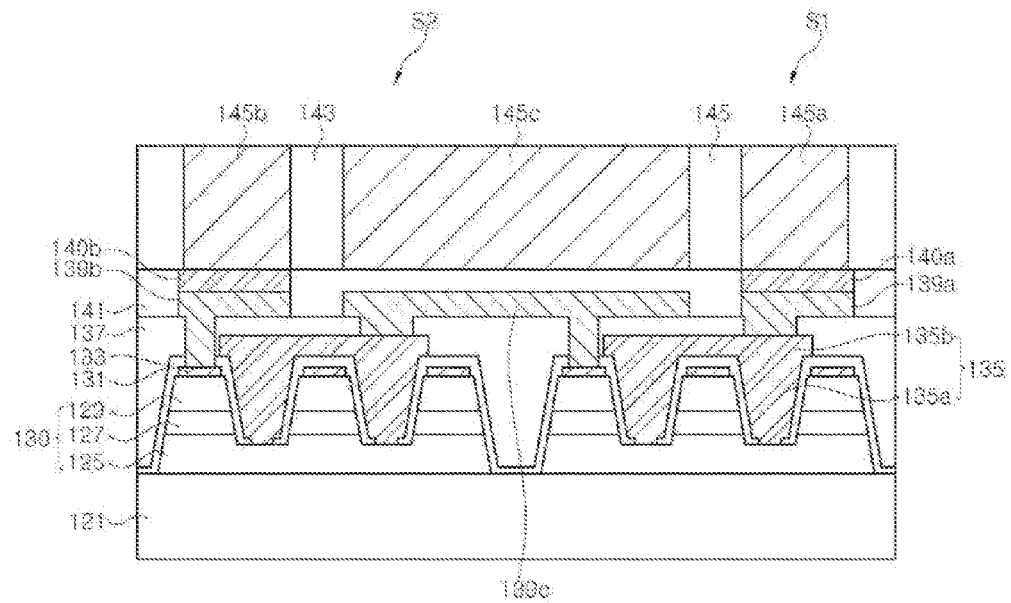


Figure 26

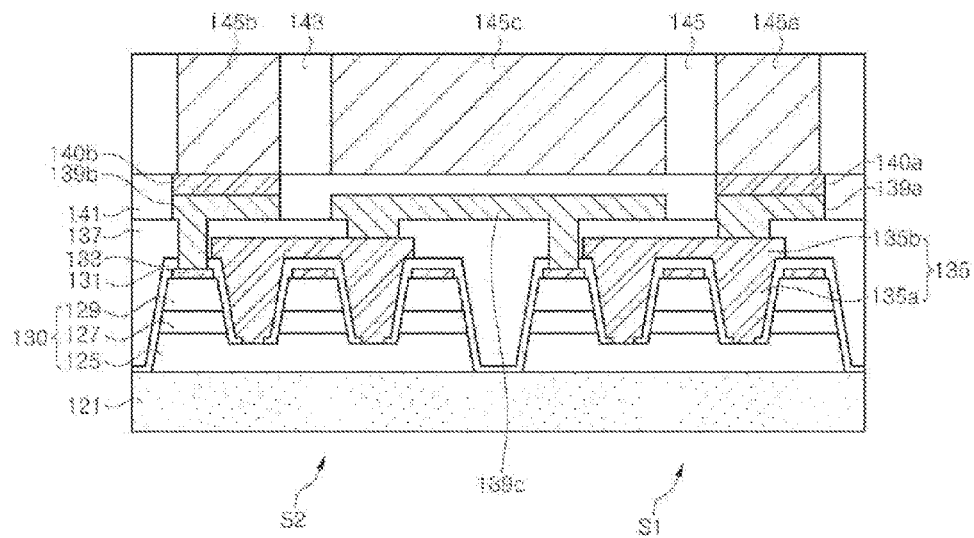
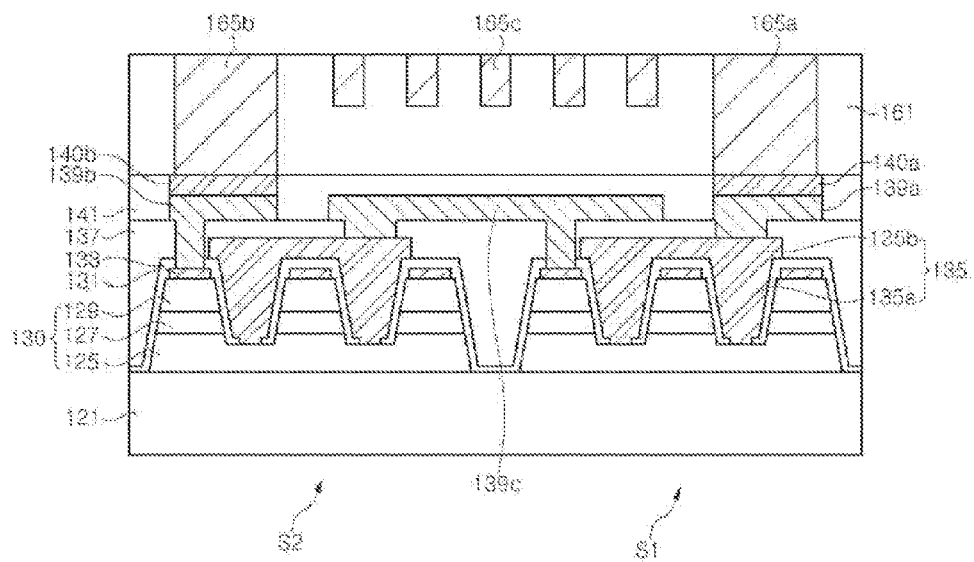


Figure 27



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# **WAFER-LEVEL LIGHT EMITTING DIODE PACKAGE AND METHOD OF FABRICATING THE SAME**

## **CROSS-REFERENCE TO RELATED APPLICATION**

This application is a continuation of, and claims the benefits and priorities to, U.S. patent application Ser. No. 13/194,317, filed on Jul. 29, 2011, and claims the benefits and priorities to Korean Patent Application No. 10-2010-0092807, filed on Sep. 24, 2010, and Korean Patent Application No. 10-2010-0092808, filed on Sep. 24, 2010, which are hereby incorporated by reference for all purposes as if fully set forth herein.

## **BACKGROUND OF THE INVENTION**

### **1. Field of the Invention**

The invention relates to a light emitting diode package and a method of fabricating the same and, more particularly, to a wafer-level light emitting diode package and a method of fabricating the same.

### **2. Description of the Background**

A light emitting diode (LED) is a semiconductor device that includes an N-type semiconductor and a P-type semiconductor, and emits light through recombination of holes and electrons. Such an LED has been used in a wide range of applications such as display devices, traffic lights, and back-light units. Further, considering the potential merits of lower power consumption and longer lifespan than existing electric bulbs or fluorescent lamps, the application range of LEDs has been expanded to general lighting by replacing existing incandescent lamps and fluorescent lamps.

The LED may be used in an LED module. The LED module is manufactured through a process of fabricating an LED chip at a wafer level, a packaging process, and a modulation process. Specifically, semiconductor layers are grown on a substrate such as a sapphire substrate, and subjected to a wafer-level patterning process to fabricate LED chips having electrode pads, followed by division into individual chips (chip fabrication process). Then, after mounting the individual chips on a lead frame or a printed circuit board, the electrode pads are electrically connected to lead terminals via bonding wires, and the LED chips are covered by a molding member, thereby providing an LED package (packaging process). Then, the LED package is mounted on a circuit board such as a metal core printed circuit board (MC-PCB), thereby providing an LED module such as a light source module (modulation process).

In the packaging process, a housing and/or the molding member may be provided to the LED chip to protect the LED chip from the external environment. In addition, a phosphor may be contained in the molding member to convert light emitted by the LED chip so that the LED package may emit a white light, thereby providing a white LED package. Such a white LED package may be mounted on the circuit board such as the MC-PCB and a secondary lens may be provided to the LED package to adjust orientation characteristics of light emitted from the LED package, thereby providing a desired white LED module.

However, it may be difficult to achieve miniaturization and satisfactory heat dissipation of the conventional LED package including the lead frame or printed circuit board. Furthermore, luminous efficiency of the LED may be deteriorated

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due to absorption of light by the lead frame or the printed circuit board, electric resistance heating by the lead terminals, and the like.

In addition, the chip fabrication process, the packaging process, and the modulation process may be separately carried out, thereby increasing time and costs for manufacturing the LED module.

Meanwhile, alternating current (AC) LEDs have been produced and marketed. The AC LED includes an LED directly connected to an AC power source to permit continuous emission of light. One example of AC LEDs, which can be used by being directly connected to a high voltage AC power source, is disclosed in U.S. Pat. No. 7,417,259, issued to Sakai, et. al.

According to U.S. Pat. No. 7,417,259, LED elements are arranged in a two-dimensional pattern on an insulating substrate, for example, a sapphire substrate, and are connected in series to form LED arrays. The LED arrays are connected in series to each other, thereby providing a light emitting device that can be operated at high voltage. Further, such LED arrays may be connected in reverse parallel to each other on the sapphire substrate, thereby providing a single-chip light emitting device that can be operated to continuously emit light using an AC power supply.

Since the AC-LED includes light emitting cells on a growth substrate, for example, on a sapphire substrate, the AC-LED restricts the structure of the light emitting cells and may limit improvement of light extraction efficiency. Thus, investigation has been made into a light emitting diode, for example, an AC-LED that is based on a substrate separation process and includes light emitting cells connected in series to each other.

## **SUMMARY OF THE INVENTION**

Exemplary embodiments of the invention provide a wafer-level LED package and a method of fabricating the same, which can be directly formed in a module on a circuit board without using a conventional lead frame or printed circuit board.

Exemplary embodiments of the invention also provide a wafer-level LED package and a method of fabricating the same, which has high efficiency and exhibits improved heat dissipation.

Exemplary embodiments of the invention also provide a method of fabricating an LED package, which may reduce manufacturing time and cost of an LED module.

Exemplary embodiments of the invention also provide an LED module and a method of fabricating the same, which has high efficiency and exhibits improved heat dissipation.

Exemplary embodiments of the invention also provide a wafer-level light emitting diode package and a method of fabricating the same, which includes a plurality of light emitting cells and may be directly formed in a module on a circuit board without using a conventional lead frame or printed circuit board.

Additional features of the invention will be set forth in the description which follows and in part will be apparent from the description, or may be learned by practice of the invention.

An exemplary embodiment of the present invention discloses an LED package including: a semiconductor stack including a first conductive type semiconductor layer, an active layer, and a second conductive type semiconductor layer; a plurality of contact holes arranged in the second conductive type semiconductor layer and the active layer, the contact holes exposing the first conductive type semiconductor layer; a first bump arranged on a first side of the semiconductor stack; the first bump being electrically connected to the

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first conductive type semiconductor layer via the plurality of contact holes; a second bump arranged on the first side of the semiconductor stack, the second bump being electrically connected to the second conductive type semiconductor layer; and a protective insulation layer covering a sidewall of the semiconductor stack.

An exemplary embodiment of the present invention also discloses a light emitting diode module including the LED package according to the aforementioned exemplary embodiments. The LED module may include a circuit board; the LED package mounted on the circuit board; and a lens to adjust an orientation angle of light emitted from the LED package.

An exemplary embodiment of the present invention also discloses a method of fabricating an LED package. The method includes forming a semiconductor stack including a first conductive type semiconductor layer, an active layer, and a second conductive type semiconductor layer on a first substrate; patterning the semiconductor stack to form a chip separation region; patterning the second conductive type semiconductor layer and the active layer to form a plurality of contact holes exposing the first conductive type semiconductor layer; forming a protective insulation layer covering a sidewall of the semiconductor stack in the chip separation region; and forming a first bump and a second bump on the semiconductor stack. The first bump is electrically connected to the first conductive type semiconductor layer via the plurality of contact holes, and the second bump is electrically connected to the second conductive type semiconductor layer.

An exemplary embodiment of the present invention also discloses a light emitting diode package. The LED package includes a plurality of light emitting cells each including a first conductive type semiconductor layer, an active layer, and a second conductive type semiconductor layer; a plurality of contact holes arranged in the second conductive type semiconductor layer and the active layer of each of the light emitting cells, the contact holes exposing the first conductive type semiconductor layer thereof; a protective insulation layer covering a sidewall of each of the light emitting cells; a connector located arranged on a first side of the light emitting cells and electrically connecting two adjacent light emitting cells to each other; a first bump arranged on the first side of the light emitting cells and electrically connected to the first conductive type semiconductor layer via the plurality of contact holes of a first light emitting cell of the light emitting cells; and a second bump arranged in the first side of the light emitting cells and electrically connected to the second conductive type semiconductor layer of a second light emitting cell of the light emitting cells.

An exemplary embodiment of the present invention also discloses a light emitting diode module including the LED package described above. The module includes a circuit board; the LED package arranged on the circuit board; and a lens to adjust an orientation angle of light emitted from the LED package.

An exemplary embodiment of the present invention also discloses a method of fabricating an LED package including a plurality of light emitting cells. The method includes forming a semiconductor stack, including a first conductive type semiconductor layer, an active layer, and a second conductive type semiconductor layer on a first substrate; patterning the semiconductor stack to form a chip separation region and a light emitting cell separation region; patterning the second conductive type semiconductor layer and the active layer to form a plurality of light emitting cells, each light emitting cell having a plurality of contact holes exposing the first conductive type semiconductor layer; forming a protective insulation

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layer covering a sidewall of the semiconductor stack in the chip separation region and the light emitting cell separation region; forming a connector connecting adjacent light emitting cells in series to each other; and forming a first bump and a second bump on the plurality of light emitting cells. Here, the first bump is electrically connected to the first conductive type semiconductor layer via the plurality of contact holes of a first light emitting cell of the light emitting cells, and the second bump is electrically connected to the second conductive type semiconductor layer of a second, light emitting cell of the light emitting cells.

It is to be understood that both the foregoing general description and the following detailed description are exemplary and explanatory and are intended to provide further explanation of the invention as claimed.

#### BRIEF DESCRIPTION OF THE DRAWINGS

The accompanying drawings, which are included to provide a further understanding of the invention and are incorporated in and constitute a part of this specification, illustrate exemplary embodiments of the invention, and together with the description serve to explain the principles of the invention.

FIG. 1 is a schematic sectional view of a light emitting diode package according to a first exemplary embodiment of the invention.

FIG. 2 is a schematic sectional view of a light emitting diode package according to a second exemplary embodiment of the invention.

FIG. 3 is a sectional view of a light emitting diode module including the light emitting diode package according to the first exemplary embodiment.

FIG. 4 to FIG. 12 show a method of fabricating the light emitting diode package according to the first exemplary embodiment, in which (a) is a plan view and (b) is a sectional view taken along line A-A of (a) in FIG. 5 to FIG. 10.

FIG. 13 is a sectional view showing a method of fabricating the light emitting diode package according to the second exemplary embodiment of the invention.

FIG. 14 is a schematic sectional view of a light emitting diode package according to a third exemplary embodiment of the invention.

FIG. 15 is a schematic sectional view of a light emitting diode package according to a fourth exemplary embodiment of the invention.

FIG. 16 is a sectional view of a light emitting diode module including the light emitting diode package according to the third exemplary embodiment.

FIG. 17 to FIG. 26 show a method of fabricating the light emitting diode package according to the third exemplary embodiment, in which (a) is a plan view and (b) is a sectional view taken along line A-A of (a) in FIG. 18 to FIG. 23.

FIG. 27 is a sectional view showing a method of fabricating the light emitting diode package according to the fourth exemplary embodiment of the invention.

#### DETAILED DESCRIPTION OF THE ILLUSTRATED EMBODIMENTS

The invention is described more fully hereinafter with reference to the accompanying drawings, in which exemplary embodiments of the invention are shown. This invention may, however, be embodied in many different forms and should not be construed as limited to the exemplary embodiments set forth herein. Rather, these exemplary embodiments are provided so that this disclosure is thorough, and will fully convey

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the scope of the invention to those skilled in the art. In the drawings, the sizes and relative sizes of layers and regions may be exaggerated for clarity. Like reference numerals in the drawings denote like elements.

It will be understood that when an element such as a layer, film, region or substrate is referred to as being “on” another element, it can be directly on the other element or intervening elements may also be present. In contrast, when an element is referred to as being “directly on” another element, there are no intervening elements present.

FIG. 1 is a schematic sectional view of an LED package 100 according to a first exemplary embodiment of the invention.

Referring to FIG. 1, the LED package 100 may include a semiconductor stack 30, a first contact layer 35, a second contact layer 31, a first insulation layer 33, a second insulation layer 37, a first electrode pad 39a, a second electrode pad 39b, a first bump 45a, and a second bump 45b. The LED package 100 may further include an insulation layer 43, a dummy bump 45c, and a wavelength converter 51.

The semiconductor stack 30 includes a first conductive type upper semiconductor layer 25, an active layer 27, and a second conductive type lower semiconductor layer 29. The active layer 27 is interposed between the upper and lower semiconductor layers 25, 29.

The active layer 27 and the upper and lower semiconductor layers 25, 29 may be composed of a III-N based compound semiconductor, for example, (Al, Ga, In)N semiconductor. Each of the upper and lower semiconductor layers 25, 29 may be a single layer or multiple layers. For example, the upper and/or lower semiconductor layers 25, 29 may include a super lattice layer in addition to a contact layer and a clad layer. The active layer 27 may have a single quantum well structure or a multi-quantum well structure. The first conductive type may be an n-type and the second conductive type may be a p-type. Alternatively, the first conductive type may be a p-type and the second conductive type may be an n-type. Since the upper semiconductor layer 25 can be formed of an n-type semiconductor layer having relatively low specific resistance, the upper semiconductor layer 25 may have a relatively high thickness. Therefore, a roughened surface R may be formed on an upper surface of the upper semiconductor layer 25, in which the roughened surface R enhances extraction efficiency of light generated in the active layer 27.

The semiconductor stack 30 has a plurality of contact holes 30a (see FIG. 5(b)) formed through the second conductive type lower semiconductor layer 29 and the active layer 27 to expose the first conductive type upper semiconductor layer, and the first contact layer 35 contacts the first conductive type upper semiconductor layer 25 exposed in the plurality of contact holes.

The second contact layer 31 contacts the second conductive type lower semiconductor layer 29. The second contact layer 31 includes a reflective metal layer to reflect light generated in the active layer 27. Further, the second contact layer 31 may form an ohmic contact with the second conductive type lower semiconductor layer 29.

The first insulation layer 33 covers the second contact layer 31. Further, the first insulation layer 33 covers a sidewall of the semiconductor stack 30 exposed in the plurality of contact holes 30a. In addition, the first insulation layer 33 may cover a side surface of the semiconductor stack 30. The first insulation layer 33 insulates the first contact layer 35 from the second contact layer 31 while insulating the second conductive type lower semiconductor layer 29 and the active layer 27 exposed in the plurality of contact holes 30a from the first contact layer 35. The first insulation layer 33 may be com-

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posed of a single layer or multiple layers, such as a silicon oxide or silicon nitride film. Alternatively, the first insulation layer 33 may be composed of a distributed Bragg reflector, which is formed by alternately stacking insulation layers having different indices of refraction, for example, SiO<sub>2</sub>/TiO<sub>2</sub> or SiO<sub>2</sub>/Nb<sub>2</sub>O<sub>5</sub>.

The first contact layer 35 is located under the first insulation layer 33 and contacts the first conductive type upper semiconductor layer 25 through the first insulation layer 33 in the plurality of contact holes 30a. The first contact layer 35 includes contact sections 35a contacting the first conductive type upper semiconductor layer 25, and a connecting section 35b connecting the contact sections 35a to each other. Therefore, the contact sections 35a are electrically connected to each other by the connecting section 35b. The first contact layer 35 is formed under some regions of the first insulation layer 33 and may be composed of a reflective metal layer.

The second insulation layer 37 covers the first contact layer 35 under the first contact layer 35. In addition, the second insulation layer 37 covers the first insulation layer 33 while covering a side surface of the semiconductor stack 30. The second insulation layer 37 may be composed of a single layer or multiple layers. Further, the second insulation layer 37 may be a distributed Bragg reflector.

The first and second electrode pads 39a, 39b are located under the second insulation layer 37. The first electrode pad 39a may be connected to the first contact layer 35 through the second insulation layer 37. Further, the second electrode pad 39b may be connected to the second contact layer 31 through the second insulation layer 37 and the first insulation layer 33.

The first bump 45a and the second bump 45b are located under the first and second electrode pads 39a, 39b to be connected thereto, respectively. The first and second bumps 45a, 45b may be formed by plating. The first and second bumps 45a, 45b are terminals electrically connected to a circuit board such as an MC-PCB and have co-planar distal ends. In addition, the first electrode pad 39a may be formed at the same level as that of the second electrode pad 39b, so that the first bump 45a and the second bump 45b may also be formed on the same plane. Therefore, the first and second bumps 45a, 45b may have the same height.

Meanwhile, the dummy bump 45c may be located between the first bump 45a and the second bump 45b. The dummy bump 45c may be formed together with the first and second bumps 45a and 45b to provide a heat passage for discharging heat from the semiconductor stack 30.

The insulation layer 43 may cover side surfaces of the first and second bumps 45a, 45b. The insulation layer 43 may also cover a side surface of the dummy bump 45c. In addition, the insulation layer 43 fills spaces between the first bump 45a, the second bump 45b and the dummy bump 45c to prevent moisture from entering the semiconductor stack 30 from outside. The insulation layer 43 also covers side surfaces of the first and second electrode pads 39a, 39b to protect the first and second electrode pads 39a, 39b from external environmental factors such as moisture. Although the insulation layer 43 may be configured to cover the overall side surfaces of the first and second bumps 45a, 45b, the invention is not limited thereto. Alternatively, the insulation layer 43 may cover the side surfaces of the first and second bumps 45a, 45b except for some regions of the side surface near distal ends of the first and second bumps.

In the present exemplary embodiment, the insulation layer 43 is illustrated as covering the side surfaces of the first and second electrode pads 39a and 39b, but the invention is not limited thereto. Alternatively, another insulation layer may be used to cover the first and second electrode pads 39a, 39b and



the insulation layer **43** may be formed under the other insulation layer. In this case, the first and second bumps **45a**, **45b** may be connected to the first and second electrode pads **39a**, **39b** through the other insulation layer.

The wavelength converter **51** may be located on the first conductive type upper semiconductor layer **25** opposite to the rest of the semiconductor stack **30**. The wavelength converter **51** may contact an upper surface of the first conductive type upper semiconductor layer **25**. The wavelength converter **51** may be a phosphor sheet having a uniform thickness without being limited thereto. Alternatively, the wavelength converter **51** may be a substrate, for example, a sapphire substrate or a silicon substrate, which is doped with an impurity for wavelength conversion.

In the present exemplary embodiment, the side surface of the semiconductor stack **30** is covered with a protective insulation layer. The protective insulation layer may include, for example, the first insulation layer **33** and/or the second insulation layer **37**. In addition, the first contact layer **35** may be covered with the second insulation layer **37** to be protected from an external environment and the second contact layer **31** may be covered with the first insulation layer **33** and the second insulation layer **37** to be protected from an external environment. The first and second electrode pads **39a**, **39b** are also protected by, for example, the insulation layer **43**. Accordingly, it is possible to prevent deterioration of the semiconductor stack **30** due to moisture.

The wavelength converter **51** may be attached to the first conductive type upper semiconductor layer **25** at a wafer-level, and then divided together with the protective insulation layer during a chip separation process. Therefore, a side surface of the wavelength converter **51** may be in a line with the protective insulation layer. That is, the side surface of the wavelength converter **51** may be flush along a straight line with a side surface of the protective insulation layer. Further, the side surface of the wavelength converter **51** may be in a line with a side surface of the insulation layer **43**. Thus, the side surfaces of the wavelength converter **51**, the protective insulation layer, and the insulation layer **43** may all be flush along a straight line.

FIG. 2 is a schematic sectional view of a light emitting diode package **200** according to a second exemplary embodiment of the invention.

Referring to FIG. 2, the LED package **200** is similar to the LED package **100** according to the above exemplary embodiment. In the present exemplary embodiment, however, first and second bumps **65a**, **65b** are formed in a substrate **61**.

Specifically, the substrate **61** includes through-holes, which have the first and second bumps **65a**, **65b** formed therein, respectively. The substrate **61** is an insulation substrate, for example, a sapphire substrate or a silicon substrate, but is not limited thereto. The substrate **61** having the first and second bumps **65a**, **65b** may be attached to a first electrode pad **39a** and a second electrode pad **39b**. In this case, to prevent the first and second electrode pads **39a**, **39b** from being exposed to the outside, an insulation layer **49** may cover side surfaces and bottom surfaces of the first and second electrode pads **39a**, **39b**. Further, the insulation layer **49** may have openings, which expose the first and second electrode pads **39a**, **39b**, and additional metal layers **67a**, **67b** are then formed in the openings. The additional metal layers **67a**, **67b** may be composed of a bonding metal.

FIG. 3 is a sectional view of a light emitting diode module including the LED package **100** according to the first exemplary embodiment.

Referring to FIG. 3, the LED module includes a circuit board **71**, for example, an MC-PCB, the LED package **100**,

and a lens **81**. The circuit board **71**, for example, the MC-PCB, has connection pads **73a**, **73b** for mounting the LED packages **100** thereon. The first and second bumps **45a**, **45b** (see FIG. 1) of the LED package **100** are connected to the connection pads **73a**, **73b**, respectively.

A plurality of LED packages **100** may be mounted on the circuit board **71** and the lens **81** may be disposed on the LED packages **100** to adjust an orientation angle of light emitted from the LED packages **100**.

In accordance with the second exemplary embodiment, the light emitting diode packages **200** may be mounted on the circuit board instead of the LED packages **100**.

FIG. 4 to FIG. 12 show a method of fabricating the LED package **100** according to the first exemplary embodiment. In FIG. 5 to FIG. 10, (a) is a plan view and (b) is a sectional view taken along line A-A of (a).

Referring to FIG. 4, a semiconductor stack **30**, which includes a first conductive type semiconductor layer **25**, an active layer **27** and a second conductive type semiconductor layer **29**, is formed on a growth substrate **21**. The growth substrate **21** may be a sapphire substrate but is not limited thereto. Alternatively, the growth, substrate **21** may be another kind of heterogeneous substrate, for example, a silicon substrate. Each of the first and second conductive type semiconductor layers **25**, **29** may be composed of a single layer or multiple layers. Further, the active layer **27** may have a single-quantum well structure or multi-quantum well structure.

The compound semiconductor layers may be formed of III-N based compound semiconductor on the growth substrate **21** by metal organic chemical vapor deposition (MOCVD) or molecular beam epitaxy (MBE).

A buffer layer (not shown) may be formed before forming the compound semiconductor layers. The buffer layer is formed to relieve lattice mismatch between the growth substrate **21** and the compound semiconductor layers and may be formed of a GaN-based material layer such as gallium nitride or aluminum nitride.

Referring to (a) and (b) of FIG. 5, the semiconductor stack **30** is patterned to form a chip (package) separation region **30b** while patterning the second conductive type semiconductor layer **29** and the active layer **27** to form a plurality of contact holes **30a** exposing the first conductive type semiconductor layer **25**. The semiconductor stack **30** may be patterned by photolithography and etching processes.

The chip separation region **30b** is a region for dividing the LED package structure into individual LED packages and side surfaces of the first conductive type semiconductor layer **25**, the active layer **27** and the second conductive type semiconductor layer **29** are exposed on the chip separation region **30b**. Advantageously, the chip separation region **30b** may be configured to expose the substrate **21** without being limited thereto.

The plurality of contact holes **30a** may have a circular shape, but is not limited thereto. The contact holes **30a** may have a variety of shapes. The second conductive type semiconductor layer **29** and the active layer **27** are exposed to sidewalls of the plurality of contact holes **30a**. As shown, the contact holes **30a** may have slanted sidewalls.

Referring to (a) and (b) of FIG. 6, a second contact layer **31** is formed on the second conductive type semiconductor layer **29**. The second contact layer **31** is formed on the semiconductor stack **30** except for regions corresponding to the plurality of contact holes **30a**.

The second contact layer **31** may include a transparent conductive oxide film such as indium tin oxide (ITO) or a reflective metal layer such as silver (Ag) or aluminum (Al).

The second contact layer **31** may be composed of a single layer or multiple layers. The second contact layer **31** may also be configured to form an ohmic contact with the second conductive type semiconductor layer **29**.

The second contact layer **31** may be formed before or after formation of the plurality of contact holes **30a**.

Referring to (a) and (b) of FIG. 7, a first insulation layer **33** is formed to cover the second contact layer **31**. The first insulation layer **33** may cover the side surface of the semiconductor stack **30** exposed to the chip separation region **30b** while covering the sidewalls of the plurality of contact holes **30a**. Here, the first insulation layer **33** may have openings **33a**, which expose the first conductive type semiconductor layer **25** in the plurality of contact holes **30a**.

The first insulation layer **33** may be composed of a single layer or multiple layers, such as a silicon oxide or silicon nitride film. Alternatively, the first insulation layer **33** may be composed of a distributed Bragg reflector, which is formed by alternately stacking insulation layers having different indices of refraction. For example, the first insulation layer **33** may be formed by alternately stacking  $\text{SiO}_2/\text{TiO}_2$  or  $\text{SiO}_2/\text{Nb}_2\text{O}_5$ . Further, the first insulation layer **33** may be formed to provide a distributed Bragg reflector having high reflectivity over a wide wavelength range of blue, green, and red light by adjusting the thickness of each of the insulation layers.

Referring to (a) and (b) of FIG. 8, a first contact layer **35** is formed on the first insulation layer **33**. The first contact layer **35** includes contact sections **35a** contacting the first conductive type upper semiconductor layer **25** exposed in the contact holes **30a**, and a connecting section **35b** connecting the contact sections **35a** to each other. The first contact layer **35** may be composed of a reflective metal layer, but is not limited thereto.

The first contact layer **35** is formed on some regions of the semiconductor stack **30**, so that the first insulation layer **33** is exposed on other regions of the semiconductor stack **30** where the first contact layer **35** is not formed.

Referring to (a) and (b) of FIG. 9, a second insulation layer **37** is formed on the first contact layer **35**. The second insulation layer **37** may be composed of a single layer or multiple layers, such as a silicon oxide or silicon nitride film. Further, the second insulation layer **37** may be composed of a distributed Bragg reflector, which is formed by alternately stacking insulation layers having different indices of refraction.

The second insulation layer **37** may cover the first contact layer **35** while covering the first insulation layer **33**. The second insulation layer **37** may also cover the side surface of the semiconductor stack **30** in the chip separation region **30b**.

The second insulation layer **37** has an opening **37a** which exposes the first contact layer **35**. Further, the second insulation layer **37** and the first insulation layer **33** are formed with an opening **37b**, which exposes the second contact layer **31**.

Referring to (a) and (b) of FIG. 10, first and second electrode pads **39a**, **39b** are formed on the second insulation layer **37**. The first electrode pad **39a** is connected to the first contact layer **35** through the opening **37a** and the second electrode pad **39b** is connected to the second contact layer **31** through the opening **37b**.

The first electrode pad **39a** is separated from the second electrode pad **39b** and each of the first and second electrode pads **39a**, **39b** may have a relatively large area from a top perspective, for example, an area not less than  $\frac{1}{3}$  of the area of the LED package.

Referring to FIG. 11, an insulation layer **43** is formed on the first and second electrode pads **39a**, **39b**. The insulation layer **43** covers the first and second electrode pads **39a**, **39b** and has grooves which expose upper surfaces of the electrode

pads **39a**, **39b**. Further, the insulation layer **43** may have a groove which exposes the second insulation layer **37** between the first and second electrode pads **39a**, **39b**.

Then, first and second bump **45a**, **45b** are formed in the grooves of the insulation layer **43**, and a dummy bump **45c** may be formed between the first bump and the second bump.

The bumps may be formed by plating, for example, electroplating, using a metallic material. If necessary, a seed layer for plating may also be formed.

In the present exemplary embodiment, the insulation layer **43** is illustrated as being directly formed on the first and second electrode pads **39a**, **39b**. In other exemplary embodiments, another insulation layer may be formed to cover the first and second electrode pads **39a**, **39b**. The other insulation layer may be configured to have openings exposing the first and second electrode pads **39a**, **39b**. Then, the processes of forming the insulation layer **43** and the bumps may be carried out.

Referring to FIG. 12, the growth substrate **21** is removed and a wavelength converter **51** is attached to the first conductive type semiconductor layer **25**. The growth substrate **21** may be removed by an optical technique such as laser lift-off (LLO), mechanical polishing or chemical etching.

Then, the exposed surface of the first conductive type semiconductor layer **25** is subjected to anisotropic etching such as photoelectrochemical (PEC) etching to form a roughened surface on the exposed first conductive type semiconductor layer **25**.

Meanwhile, the wavelength converter such as a phosphor sheet containing phosphors may be attached to the first conductive type semiconductor layer **25**.

Alternatively, the growth substrate **21** may contain an impurity for converting a wavelength of light generated in the active layer **27**. In this case, the growth substrate **21** may be used as the wavelength converter **51**.

Then, the LED package structure is divided into individual packages along the chip separation region **30b**, thereby providing finished LED packages **100**. At this time, the second insulation layer **37** is cut together with the wavelength converter **51** so that cut planes thereof can be formed in a line.

FIG. 13 is a sectional view showing a method of fabricating the LED package **200** according to the second exemplary embodiment of the present invention.

Referring to FIG. 13, in the method of fabricating the LED package **200** according to the present exemplary embodiment, the processes until the first and second electrode pads **39a**, **39b** are formed are the same as those of the method of fabricating the LED package **100** described above (FIGS. 10 (a) and (b)).

After the first and second electrode pads **39a**, **39b** are formed, an insulation layer **49** is formed to cover the first and second electrode pads **39a**, **39b**. The insulation layer **49** may cover side surfaces of the first and second electrode pads **39a**, **39b** to protect the first and second electrode pads **39a**, **39b**. The insulation layer **49** has openings which expose the first and second electrode pads **39a**, **39b**. Additional metal layers **67a**, **67b** are then formed in the openings. The additional metal layers **67a**, **67b** may be composed of a bonding metal.

The substrate **61** is bonded to the first and second electrode pads **39a**, **39b**. The substrate **61** may have through-holes, in which the first and second bumps **65a**, **65b** may be formed.

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Further, the first and second bumps may be formed at distal ends thereof with pads **69a**, **69b**. The substrate **61** having the first and second bumps **65a**, **65b** and the pads **69a**, **69b** may be separately prepared and bonded to a wafer having the first and second electrode pads **39a**, **39b**.

Then, as described with reference to FIG. **12**, the growth substrate **21** is removed and a wavelength converter **51** may be attached to the first conductive type semiconductor layer **25**, followed by division of the LED package structure into individual LED packages. As a result, the finished LED packages **200** as described in FIG. **2** are provided.

FIG. **14** is a sectional view of an LED package **300** according to a third exemplary embodiment of the present invention.

Referring to FIG. **14**, the LED package **300** may include a semiconductor stack **130**, which is divided into a plurality of light emitting cells (only two light emitting cells **S1**, **S2** are shown herein), a first contact layer **135**, a second contact layer **131**, a first insulation layer **133**, a second insulation layer **137**, a first electrode pad **139a**, a second electrode pad **139b**, a connector **139c** connecting adjacent light emitting cells to each other in series, a first bump **145a** and a second bump **145b**. Further, the LED package **300** may include a third insulation layer **141**, an insulation layer **143**, a dummy bump **145c**, a wavelength converter **151**, and additional metal layers **140a**, **140b**.

The semiconductor stack **130** includes a first conductive type upper semiconductor layer **125**, an active layer **127**, and a second conductive type lower semiconductor layer **129**. The semiconductor stack **130** of the present exemplary embodiment is similar to the semiconductor stack **30** described in FIG. **1**, and a detailed description thereof will be omitted herein.

Each of the light emitting cells **S1**, **S2** has a plurality of contact holes **130a** (see FIG. **18(b)**) extending through the second conductive type lower semiconductor layer **120** and the active layer **127** to expose the first conductive type upper semiconductor layer, and the first contact layer **135** contacts the first conductive type upper semiconductor layer **125** exposed in the plurality of contact holes. The light emitting cells **S1**, **S2** are separated from each other by a cell separation region **130b** (see FIG. **18(b)**).

The second contact layer **131** contacts the second conductive type lower semiconductor layer **129** of each of the light emitting cells **S1**, **S2**. The second contact layer **131** includes a reflective metal layer to reflect light generated in the active layer **127**. Further, the second contact layer **131** may form an ohmic contact with the second conductive type lower semiconductor layer **129**.

The first insulation layer **133** covers the second contact layer **131**. Rather, the first insulation layer **133** covers a side-wall of the semiconductor stack **130** exposed in the plurality of contact holes **130a**. In addition, the first insulation layer **133** may cover a side surface of each of the light emitting cells **S1**, **S2**. The first insulation layer **133** insulates the first contact layer **135** from the second contact layer **131** while insulating the second conductive type lower semiconductor layer **129** and the active layer **127** exposed in the plurality of contact holes **130a** from the first contact layer **135**. The first insulation layer **133** may be composed of a single layer or multiple layers, such as a silicon oxide or silicon nitride film. Furthermore, the first insulation layer **133** may be composed of a distributed Bragg reflector, which is formed by alternately stacking insulation layers having different indices of refraction, for example,  $\text{SiO}_2/\text{TiO}_2$  or  $\text{SiO}_2/\text{Nb}_2\text{O}_5$ .

The first contact layer **135** is located under the first insulation layer **133** and contacts the first conductive type upper semiconductor layer **125** through the first insulation layer **133**

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in the plurality of contact holes **130a** in each of the light emitting cells **S1**, **S2**. The first contact layer **135** includes contact sections **135a** contacting the first conductive type upper semiconductor layer **125**, and a connecting section **135b** connecting the contact sections **135a** to each other. Therefore, the contact sections **135a** are electrically connected to each other by the connecting section **135b**. The first contact layers **135** located under the respective light emitting cells **S1**, **S2** are separated from each other and formed under some regions of the first insulation layer **133**. The first contact layer **135** may be composed of a reflective metal layer.

The second insulation layer **137** covers the first contact layer **133** under the first contact layer **135**. In addition, the second insulation layer **137** may cover the first insulation layer **133** while covering the side surface of each of the light emitting cells **S1**, **S2**. The second insulation layer **137** may be composed of a single layer or multiple layers. Alternatively, the second insulation layer **37** may be composed of a distributed Bragg reflector.

The first electrode pad **139a** and the second electrode pad **139b** are located under the second insulation layer **137**. The first electrode pad **139a** may be connected to the first contact layer **135** of a first light emitting cell **S1** through the second insulation layer **137**. Further, the second electrode pad **139b** may be connected to the second contact layer **131** of a second light emitting cell **S2** through the second insulation layer **137** and the first insulation layer **133**.

The connector **139c** is located under the second insulation layer **137** and electrically connects two adjacent light emitting cells **S1**, **S2** to each other through the second insulation layer **137**. The connector **139c** may connect the second contact layer **131** of one light emitting cell **S1** to the first contact layer **135** of another light emitting cell **S2** adjacent thereto, so that the two light emitting cells **S1**, **S2** are connected in series to each other.

In the present exemplary embodiment, two light emitting cells **S1**, **S2** are illustrated. However, it should be understood that two or more light emitting cells may be connected in series to each other by a plurality of connectors **139c**. Here, the first and second electrode pads **139a**, **139b** may be connected in series to the light emitting cells **S1**, **S2** located at opposite ends of such series array.

Meanwhile, the third insulation layer **141** may cover the first electrode pad **139a**, the second electrode pad **139b** and the connector **139c** under the first electrode pad **139a**, the second electrode pad **139b** and the connector **139c**. The third insulation layer **141** may have an opening exposing the first electrode pad **139a** and the second electrode pad **139b**. The third insulation layer **141** may be formed of a silicon oxide or silicon nitride film.

The first bump **145a** and the second bump **145b** are located under the first and second electrode pads **139a**, **139b**, respectively. The first and second bumps **145a**, **145b** may be formed by plating. The first and second bumps **145a**, **145b** are terminals electrically connected to a circuit board such as an MC-PCB and have distal ends coplanar with each other. In addition, the first electrode pad **139a** may be formed at the same level as that of the second electrode pad **139b**, so that the first bump **145a** and the second bump **145b** may also be formed on the same plane. Therefore, the first and second bumps **145a**, **145b** may have the same height.

The additional metal layers **140a**, **140b** may be interposed between the first bump **145a** and the first electrode pad **139a** and between the second bump **145b** and the second electrode pad **139b**. Here, the additional metal layers **140a**, **140b** are provided to form the first and second electrode pads **139a**, **139b** to be higher than the connector **139c** and may be located

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inside openings of the third insulation layer **141**. The first and second electrode pads **139a**, **139b** and the additional metal layers **140a**, **140b** may constitute final electrode pads.

Meanwhile, the dummy bump **145c** may be located between the first bump **145a** and the second bump **145b**. The dummy bump **145c** may be formed together with the first and second bump **145a**, **145b** to provide a heat passage for discharging heat from the light emitting cells **S1**, **S2**. The dummy bump **145c** is separated from the connector **139c** by the third insulation layer **141**.

The insulation layer **143** may cover side surfaces of the first and second bumps **145a**, **145b**. The insulation layer **143** may also cover a side surface of the dummy bump **145c**. In addition, the insulation layer **143** fills spaces between the first bump **145a**, the second bump **145b** and the dummy bump **145c** to prevent moisture from entering the semiconductor stack **130** from outside. Although the insulation layer **143** may be configured to cover the overall side surfaces of the first and second bumps **145a**, **145b**, the invention is not limited thereto. Alternatively, the insulation layer **143** may cover the side surfaces of the first and second bumps **145a**, **145b** except for some regions of the side surface near distal ends of the first and second bumps.

The wavelength converter **151** may be located on the light emitting cells **S1**, **S2**. The wavelength converter **151** may contact an upper surface of the first conductive type upper semiconductor layer **125**. The wavelength converter **151** also covers a cell separation region **130b** and a chip separation region. The wavelength converter **151** may be a phosphor sheet having a uniform thickness without being limited thereto. Alternatively, the wavelength converter **151** may be a substrate, for example, a sapphire substrate or a silicon substrate, which is doped with an impurity for wavelength conversion.

In the present embodiment, the side surfaces of the light emitting cells **S1**, **S2** are covered with a protective insulation layer. The protective insulation layer may include, for example, the first insulation layer **133** and/or the second insulation layer **137**. In addition, the first contact layer **135** may be covered with the second insulation layer **137** to be protected from external environment and the second contact layer **131** may be covered with the first insulation layer **133** and the second insulation layer **137** to be protected from external environment. Further, the first and second electrode pads **139a**, **139b** are also protected by, for example, the third insulation layer **141**. Accordingly, it is possible to prevent deterioration of the light emitting cells **S1**, **S2** due to moisture.

The wavelength converter **151** may be attached to the first conductive type upper semiconductor layer **125** at a wafer-level, and then divided together with the protective insulation layer during a chip separation process (or package separation process). Therefore, a side surface of the wavelength converter **151** may be in a line with the protective insulation layer. Further, the side surface of the wavelength converter **151** may be in a line with a side surface of the insulation layer **143**.

FIG. **15** is a schematic sectional view of a light emitting diode package **400** according to a fourth exemplary embodiment of the present invention.

Referring to FIG. **15**, the LED package **400** is similar to the LED package **300** according to the above exemplary embodiment. In present exemplary embodiment, however, first and second bumps **165a**, **165b** are formed in a substrate **161**.

Specifically, the substrate **161** includes through-holes, which have the first and second bumps **165a**, **165b** formed therein, respectively. The substrate **161** is an insulation substrate, for example, a sapphire substrate or a silicon substrate, but is not limited thereto.

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The substrate **161** having the first and second bumps **165a**, **165b** may be attached to a third insulation layer **141**, and the first and second bumps **165a**, **165b** may be connected to first and second electrode pads **139a**, **139b**, respectively. Here, the first and second bumps **165a**, **165b** may be bonded to additional metal layers **140a**, **140b**, respectively.

FIG. **16** is a sectional view of a light emitting diode module including the LED packages **300** according to the third exemplary embodiment on a circuit board.

Referring to FIG. **16**, the LED module includes a circuit board **171**, for example, an MC-PCB, the LED package **300**, and a lens **181**. The circuit board **171**, for example, the MC-PCB, has connection pads **173a**, **173b** for mounting the LED packages **300** thereon. The first and second bumps **145a**, **145b** (see FIG. **14**) of the LED package **300** are connected to the Connection pads **73a**, **73b**, respectively.

A plurality of LED packages **300** may be mounted on the circuit board **171** and the lens **181** may be disposed on the LED packages **300** to adjust an orientation angle of light emitted from the LED packages **300**.

In other exemplary embodiments, instead of the LED packages **300**, the light emitting diode packages **400** may be mounted on the circuit board.

FIG. **17** to FIG. **25** show a method of fabricating the LED package **300** according to the third exemplary embodiment. In FIG. **18** to FIG. **23**, (a) is a plan view and (b) is a sectional view taken along line A-A of (a).

Referring to FIG. **17**, a semiconductor stack **130**, which includes a first conductive type semiconductor layer **125**, an active layer **127** and a second conductive type semiconductor layer **129**, is formed on a growth substrate **121**. The growth substrate **121** and the semiconductor stack **130** are similar to the substrate **21** and the semiconductor stack **30** described with reference to FIG. **4**, and a detailed description thereof will thus be omitted herein.

Referring to (a) and (b) of FIG. **18**, the semiconductor stack **130** is patterned to form a chip (package) separation region **130c** and a cell separation region **130b** while patterning the second conductive type semiconductor layer **129** and the active layer **127** to form light emitting cells **S1**, **S2**, each having a plurality of contact holes **130a** exposing the first conductive type semiconductor layer **125**. The semiconductor stack **130** may be patterned by photolithography and etching processes.

The chip separation region **130c** is a region for dividing the LED package structure into individual LED packages and side surfaces of the first conductive type semiconductor layer **125**, the active layer **127** and the second conductive type semiconductor layer **129** are exposed at the chip separation region **130c**. Advantageously, the chip separation region **130c** and the cell separation region **130b** may be configured to expose the substrate **121** without being limited thereto.

The plurality of contact holes **130a** may have a circular shape, but is not limited thereto. The contact holes **130** may have a variety of shapes. The second conductive type semiconductor layer **129** and the active layer **127** are exposed to sidewalls of the plurality of contact holes **130a**. The contact holes **130a** may have slanted sidewalls.

Referring to (a) and (b) of FIG. **19**, a second contact layer **131** is formed on the second conductive type semiconductor layer **129**. The second contact layer **131** is formed on the semiconductor stack **130** in each of the light emitting cells **S1**, **S2** except for regions corresponding to the plurality of contact holes **130a**.

The second contact layer **131** may include a transparent conductive oxide film such as indium tin oxide (ITO) or a reflective metal layer such as silver (Ag) or aluminum (Al).

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The second contact layer **131** may be composed of a single layer or multiple layers. The second contact layer **131** may also be configured to form an ohmic contact with the second conductive type semiconductor layer **129**.

The second contact layer **131** may be formed before or after the formation of the plurality of contact holes **130a**

Referring to (a) and (b) of FIG. **20**, a first insulation layer **133** is formed to cover the second contact layer **131**. The first insulation layer **133** may cover the side surface of each of the light emitting cells **S1**, **S2** while covering the sidewalls of the plurality of contact holes **130a**. Here, the first insulation layer **133** may have openings **133a**, which expose the first conductive type semiconductor layer **125** in the plurality of contact holes **130a**.

The first insulation layer **133** may be composed of a single layer or multiple layers, such as a silicon oxide or silicon nitride film. In addition, the first insulation layer **133** may be composed of a distributed Bragg reflector, which is formed by alternately stacking insulation layers having different indices of refraction. For example, the first insulation layer **133** may be formed by alternately stacking  $\text{SiO}_2/\text{TiO}_2$  or  $\text{SiO}_2/\text{Nb}_2\text{O}_5$ . Further, the first insulation layer **133** may be formed to provide a distributed Bragg reflector having high reflectivity over a wide wavelength range of blue, green, and red light by adjusting the thickness of each of the insulation layers.

Referring to (a) and (b) of FIG. **21**, a first contact layer **135** is formed on the first insulation layer **133**. The first contact layer **135** is formed on each of the light emitting cells **S1**, **S2**, and includes contact sections **35a** contacting the first conductive type upper semiconductor layer **125** exposed in the contact holes **130a** and a connecting section **135b** connecting the contact sections **135a** to each other. The first contact layer **135** may be composed of a reflective metal layer, but is not limited thereto.

The first contact layer **135** is formed on some regions of each of the light emitting cells **S1**, **S2**, so that the first insulation layer **133** is exposed at other regions of the semiconductor stack **130** where the first contact layer **135** is not formed.

Referring to (a) and (b) of FIG. **22**, a second insulation layer **137** is formed on the first contact layer **135**. The second insulation layer **137** may be composed of a single layer or multiple layers, such as a silicon oxide or silicon nitride film. Alternatively, the second insulation layer **137** may be composed of a distributed Bragg reflector, which is formed by alternately stacking insulation layers having different indices of refraction.

The second insulation layer **137** may cover the first contact layer **135** while covering the first insulation layer **133**. The second insulation layer **137** may also cover the side surface of each of the light emitting cells **S1**, **S2**. In addition, the second insulation layer **137** may fill in the chip separation region **130c** and the cell separation region **130b**.

The second insulation layer **137** has an opening **137a** which exposes the first contact layer **135** of each of the light emitting cells **S1**, **S2**. Further, the second insulation layer **137** and the first insulation layer **133** are formed with an opening **137b**, which exposes the second contact layer **131**.

Referring to (a) and (b) of FIG. **23**, a connector **139c** and first and second electrode pads **139a**, **139b** are formed on the second insulation layer **137**. The first electrode pad **139a** is connected to the first contact layer **135** of a first light emitting cell **S1** through the opening **137a** and the second electrode pad **139b** is connected to the second contact layer **131** of a second light emitting cell **S2** through the opening **137b**. Further, the connector **139c** connects the first contact layer **135**

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and the second contact layer **131** of adjacent light emitting cells **S1**, **S2** to each other in series through the openings **137a**, **137b**.

Referring to FIG. **24**, a third insulation layer **141** is formed on the first and second electrode pads **139a**, **139b** and the connector **139c**. The third insulation layer **141** covers the first and second electrode pads **139a**, **139b** and the connector **139c**, and has grooves which expose upper surfaces of the electrode pads **139a**, **139b**. Meanwhile, the third insulation layer **141** may have additional metal layers **140a**, **140b** formed in the grooves thereof. The additional metal layers **140a**, **140b** increase the height of the electrode pads **139a**, **139b**, such that final electrode pads may have a greater height than the connector **139c**. The additional metal layers **140a**, **140b** may be formed before the formation of the third insulation layer **141**. Upper surfaces of the additional metal layers **140a**, **140b** may be substantially coplanar with an upper surface of the third insulation layer **141**.

Referring to FIG. **25**, a patterned insulation layer **143** is formed on the third insulation layer **141**. The patterned insulation layer **143** has grooves, which expose the upper side of the first and second electrode pads **139a**, **139b**, for example, the additional metal layers **140a**, **140b**. Further, the patterned insulation layer **143** may have a groove exposing the third insulation layer **141** between the first electrode pad **139a** and the second electrode pad **139b**.

Then, first and second bumps **145a**, **145b** are formed in the grooves of the insulation layer **143** and a dummy bump **145c** may be formed between the first and second bumps.

The bumps may be formed by plating, for example, electroplating. As needed, a seed layer for plating may also be formed.

After the first and second bumps **145a**, **145b** are formed, the insulation layer **143** may be removed. For example, the insulation layer **143** may be formed of a polymer such as photoresist and may be removed after the bumps are formed. Alternatively, the insulation layer **143** may remain to protect the side surfaces of the first and second bumps **145a**, **145b**.

Referring to FIG. **26**, the growth substrate **121** is removed and a wavelength converter **151** is attached to the light emitting cells **S1**, **S2**. The growth substrate **21** may be removed by an optical technique such as laser lift-off (LLO), mechanical polishing or chemical etching.

Then, the exposed surface of the first conductive type semiconductor layer **125** is subjected to anisotropic etching such as PEC etching to form a roughened surface on the exposed first conductive type semiconductor layer **125**.

Meanwhile, the wavelength converter **151**, such as a phosphor sheet containing phosphors, may be attached to the first conductive type semiconductor layer **125**.

Alternatively, the growth substrate **121** may contain an impurity for converting a wavelength of light generated in the active layer **127**. In this case, the growth substrate **121** may be used as the wavelength converter **151**.

Then, the LED package structure is divided into individual packages along the chip separation region **130c**, thereby providing finished LED packages **300**. At this time, the second insulation layer **137** is cut together with the wavelength converter **151** so that cut planes thereof can be formed in a line.

FIG. **27** is a sectional view explaining a method of fabricating the LED package **400** according to the fourth exemplary embodiment of the invention.

Referring to FIG. **27**, in the method of fabricating the LED package **400** according to this embodiment, the processes until the third insulation layer **141** and the additional metal

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layers **140a**, **1140b** are formed are the same as those of the method of fabricating the LED package **300** described above (FIG. **24**).

In the present exemplary embodiment, the substrate **161** is bonded to the third insulation layer **141**. The substrate **161** may have through-holes, in which the first and second bumps **165a**, **165b** may be formed. Further, the first and second bumps **165a**, **165b** may be formed at distal ends thereof with pads (not shown). In addition, the substrate **161** may have grooves partially formed on a lower surface thereof and filled with a metallic material **165c**. The metallic material **165c** improves substrate heat dissipation.

Alternatively, the substrate **161** having the first and second bumps **165a**, **165b** may be separately prepared and bonded to a wafer having the first and second electrode pads **139a**, **139b**. The first and second bumps **165a**, **165b** may be electrically connected to first and second electrode pads **139a**, **139b**, respectively.

Then, as described with reference to FIG. **26**, the growth substrate **121** is removed and the wavelength converter **151** may be attached to the light emitting cells **S1**, **S2**, followed by division of the LED package structure into individual LED packages. As a result, the finished LED packages **400** as described in FIG. **15** are provided.

As such, the exemplary embodiments of the invention provide wafer-level LED packages which can be directly formed on a circuit board for a module without using a conventional lead frame or printed circuit board. Accordingly, the LED package may have high efficiency and exhibit improved heat dissipation while reducing time and cost for fabrication of the LED package. In addition, an LED module having the LED package mounted thereon may have high efficiency and exhibit improved heat dissipation.

Further, the LED package may include a plurality of light emitting cells connected in series to each other and arrays connected in reverse parallel to each other. Further, the plurality of light emitting cells may be connected to a bridge rectifier and may be used to form a bridge rectifier. Therefore, the LED module including the LED package may be operated by AC power without a separate AC/DC converter.

Although the invention has been illustrated with reference to some exemplary embodiments in conjunction with the drawings, it will be apparent to those skilled in the art that various modifications and changes can be made to the invention without departing from the spirit and scope of the invention. Further, it should be understood that some features of a certain embodiment may also be applied to other embodiment without departing from the spirit and scope of the invention. Therefore, it should be understood that the embodiments are provided by way of illustration only and are given to provide complete disclosure of the invention and to provide thorough understanding of the invention to those skilled in the art. Thus, it is intended that the invention covers the modifications and variations provided they fall within the scope of the appended claims and their equivalents.

What is claimed is:

1. A method of fabricating a light emitting diode (LED), the method comprising:

forming a semiconductor stack over a first substrate, the semiconductor stack comprising a first conductive type semiconductor layer, an active layer, and a second conductive type semiconductor layer;

patterning the second conductive type semiconductor layer and the active layer to form a plurality of contact holes exposing at least a portion of the first conductive type semiconductor layer;

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forming a protective insulation layer covering a sidewall of the semiconductor stack;

forming a first pad and a second pad over the semiconductor stack; and

forming a dummy bump to provide a heat passage for discharging heat from the semiconductor stack,

wherein the first pad is electrically connected to the first conductive type semiconductor layer via the plurality of contact holes,

the second pad is electrically connected to the second conductive type semiconductor layer.

2. The method of claim 1, wherein the first substrate comprises an impurity for converting a wavelength of light generated in the active layer.

3. The method of claim 1, further comprising:

removing the first substrate to expose the first conductive type semiconductor layer.

4. The method of claim 3, further comprising:

attaching a phosphor sheet to the exposed first conductive type semiconductor layer.

5. The method of claim 1,

wherein forming the protective insulation layer comprises forming a first insulation layer and a second insulation layer that cover the sidewall of the semiconductor stack at different positions.

6. The method of claim 5, further comprising:

forming a second contact layer over the second conductive type semiconductor layer; and

forming the first insulation layer to cover the second contact layer and sidewalls of the plurality of contact holes, the first insulation layer comprising openings exposing the first conductive type semiconductor layer.

7. The method of claim 6, further comprising:

forming a first contact layer over the first insulation layer, wherein the first contact layer includes at least a portion contacting the exposed first conductive type semiconductor layer.

8. The method of claim 7, further comprising:

forming the second insulation layer to cover at least a portion of the first contact layer;

patterning the second insulation layer to form an opening exposing the first contact layer; and

patterning the first insulation layer and the second insulation layer to form an additional opening exposing the second contact layer.

9. The method of claim 8,

wherein the first pad and the second pad are electrically connected to the first contact layer and the second contact layer through the opening and the additional opening, respectively.

10. The method of claim 3, further comprising:

bonding a second substrate over the first pad and the second pad before the removing of the first substrate.

11. A method of fabricating a light emitting diode (LED), the method comprising:

forming a semiconductor stack over a first substrate, the semiconductor stack comprising a first conductive type semiconductor layer, an active layer, and a second conductive type semiconductor layer;

patterning the semiconductor stack to form a chip separation region and a light emitting cell separation region;

patterning the second conductive type semiconductor layer and the active layer to form a plurality of light emitting cells including a first light emitting cell and a second light emitting cell, each light emitting cell comprising a plurality of contact holes exposing at least a portion of the first conductive type semiconductor layer;

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forming a protective insulation layer covering a sidewall of the semiconductor stack in the chip separation region and the light emitting cell separation region;  
forming a connector connecting adjacent light emitting cells to each other in series; and

forming a first bump and a second bump over the plurality of light emitting cells,

wherein the first bump is electrically connected to the first conductive type semiconductor layer via the plurality of contact holes of the first light emitting cell, and the second bump being electrically connected to the second conductive type semiconductor layer of the second light emitting cell.

12. The method of claim 11, wherein the first substrate comprises an impurity for converting a wavelength of light generated in the active layer.

13. The method of claim 12, further comprising:  
removing the first substrate to expose the light emitting cells.

14. The method of claim 13, further comprising:  
attaching a phosphor sheet to the exposed light emitting cells.

15. The method of claim 11, wherein the forming of the protective insulation layer comprises forming a first insulation layer and a second insulation layer that cover the sidewall of the semiconductor stack at different positions.

16. The method of claim 15, further comprising:  
forming a second contact layer over the second conductive type semiconductor layer of each of the light emitting cells;

forming the first insulation layer to cover the second contact layer of each of the light emitting cells and sidewalls of the plurality of contact holes, the first insulation layer comprising openings exposing the first conductive type semiconductor layer; and

forming a first contact layer over the first insulation layer of each of the light emitting cells,

wherein the first contact layer includes at least a portion contacting the exposed first conductive type semiconductor layer.

17. The method of claim 16, further comprising:  
forming the second insulation layer to cover at least a portion of the first contact layer of each of the light emitting cells;

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patterning the second insulation layer of each of the light emitting cells to form an opening exposing the first contact layer;

patterning the first insulation layer and the second insulation layer to form an additional opening exposing the second contact layer; and

forming a first electrode pad and a second electrode pad on the second insulation layer, the first electrode pad and the second electrode pad to be respectively connected to the first contact layer of the first light emitting cell and the second contact layer of the second light emitting cell through the openings,

wherein the connector is formed over the second insulation layer and contacts the first contact layer and second contact layer of each of the adjacent light emitting cells through the opening and the additional opening, and the first bump and the second bump are electrically connected to the first electrode pad and the second electrode pad, respectively.

18. The method of claim 16, wherein the forming of the first bump and the second bump comprises forming an insulation layer pattern having openings exposing regions of the first electrode pad and the second electrode pad, and plating the exposed regions of the first electrode pad and the second electrode pad with a metallic material.

19. The method of claim 18, further comprising:  
forming a dummy bump between the first bump and the second bump.

20. The method of claim 19, further comprising: before the forming of the dummy bump, forming a third insulation layer to cover the first electrode pad, the second electrode pad, and the connector, and patterning the third insulation layer to expose the first electrode pad and the second electrode pad.

21. The method of claim 16, wherein the forming of the first bump and the second bump comprises forming a plurality of through-holes in an insulation substrate, filling the through-holes with a metallic material, and bonding the metallic material to the first electrode pad and the second electrode pad.

22. The method of claim 19, further comprising: before the forming of the dummy bump, forming a third insulation layer to cover the first electrode pad, the second electrode pad, and the connector, and patterning the third insulation layer to expose the first electrode pad and the second electrode pad.

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